



# A Gecko-Inspired Chip-Integrated Reversible Adhesive

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Mechanical Engineering

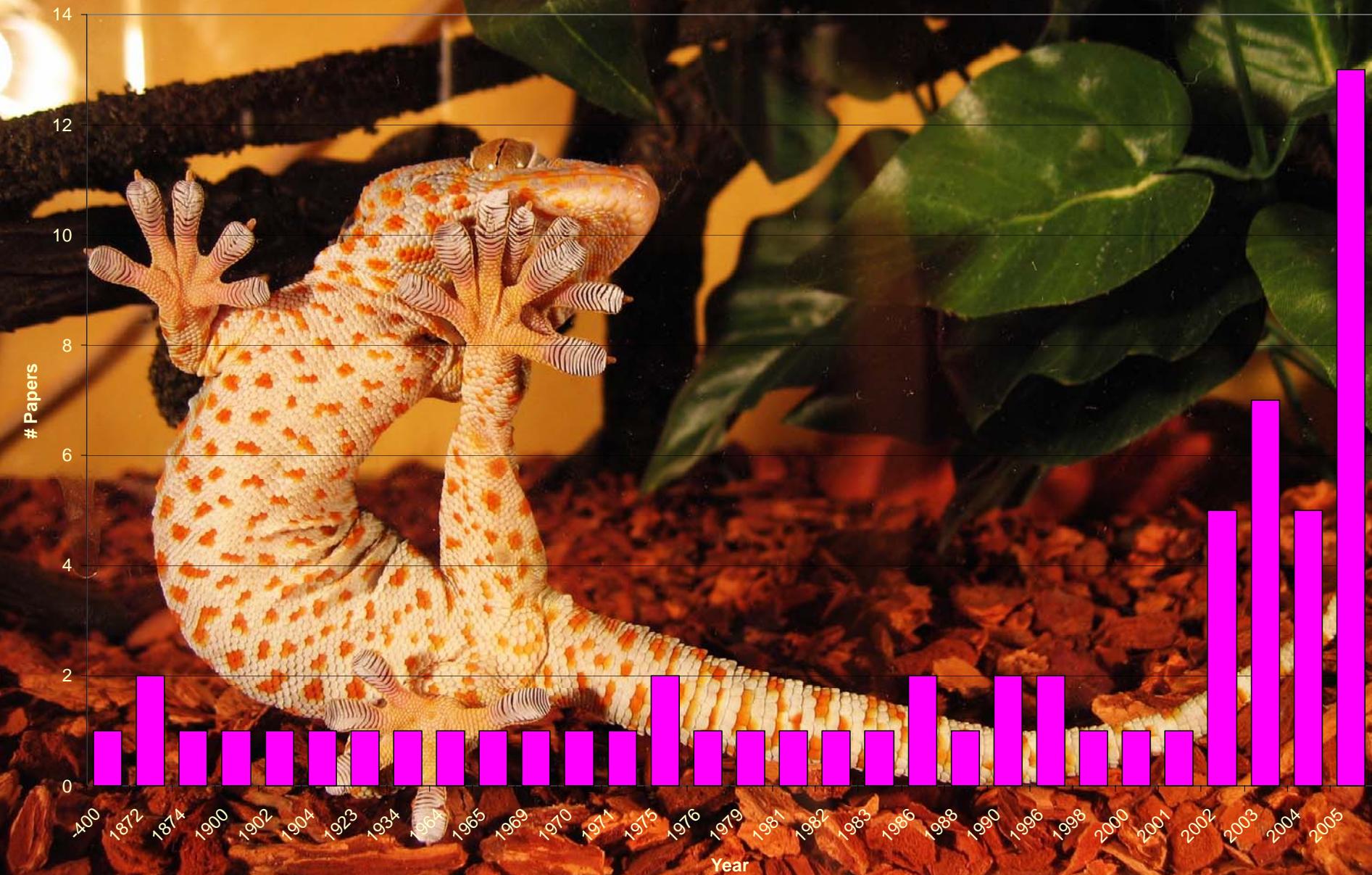
Michael Northen, Postdoc  
Institute for Collaborative Biotechnologies

University of California, Santa Barbara

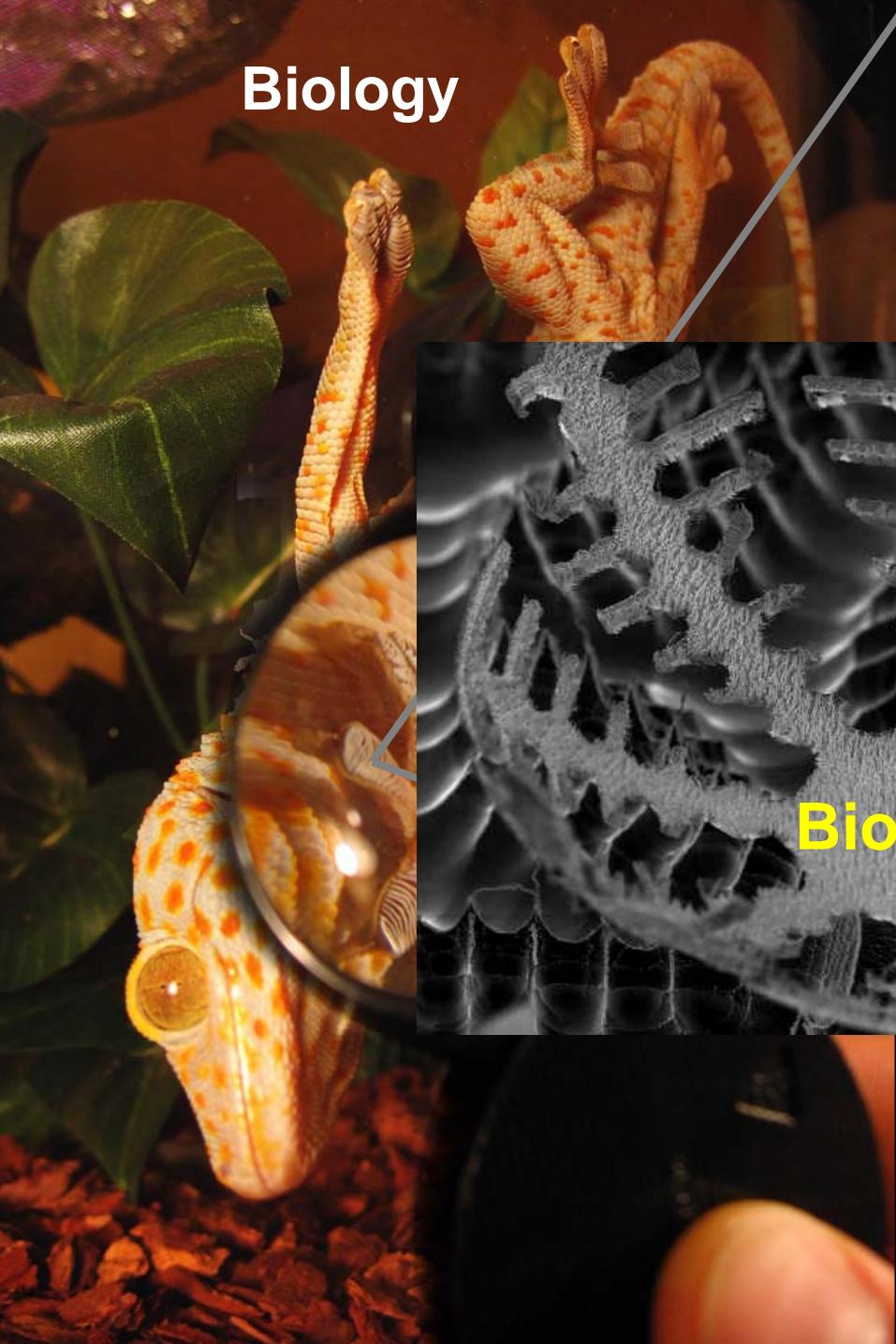
# Outline

- **Introduction & Motivation**
- Gecko Adhesion Mechanism
- Integrated Micro/Nanostructures
  - adhesion testing
- Adhesion Control
  - adhesion testing

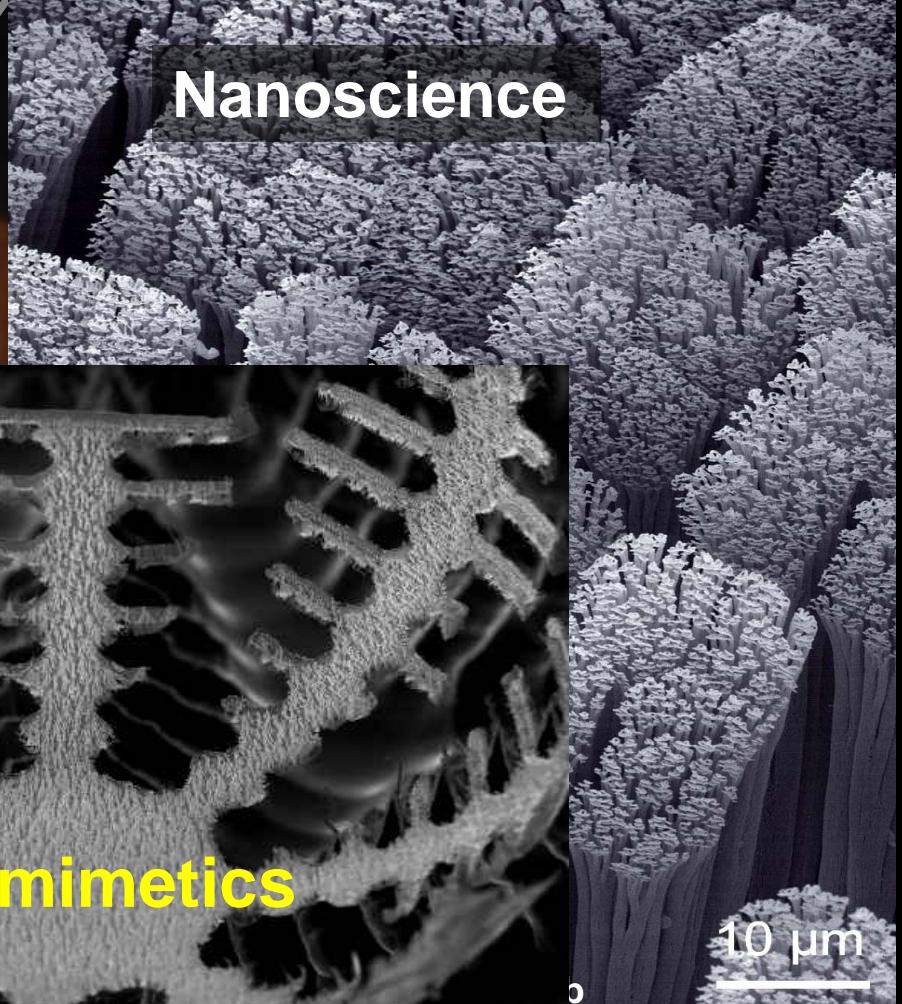
# Gecko Paper Frequency



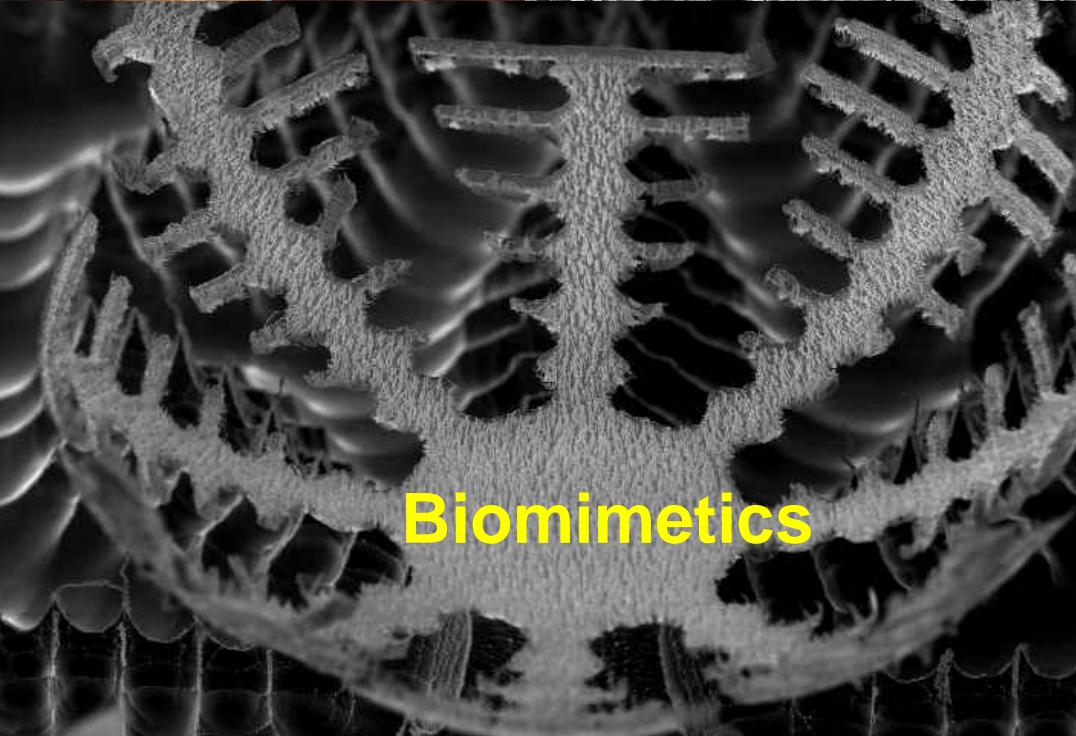
**Biology**



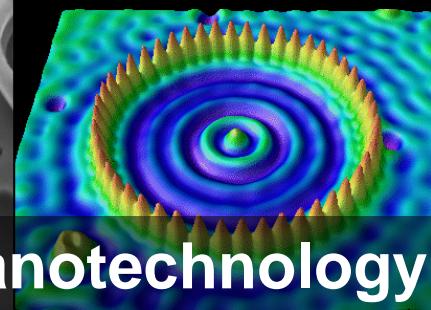
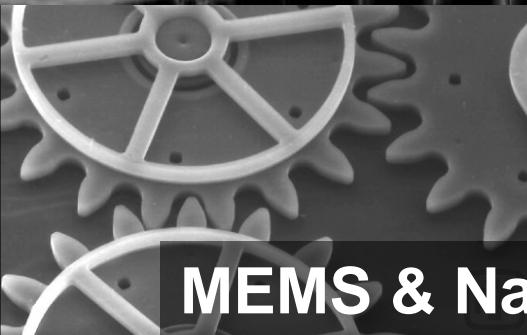
**Nanoscience**



**Biomimetics**



**MEMS & Nanotechnology**

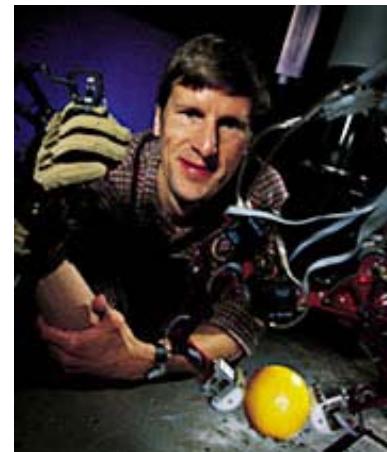
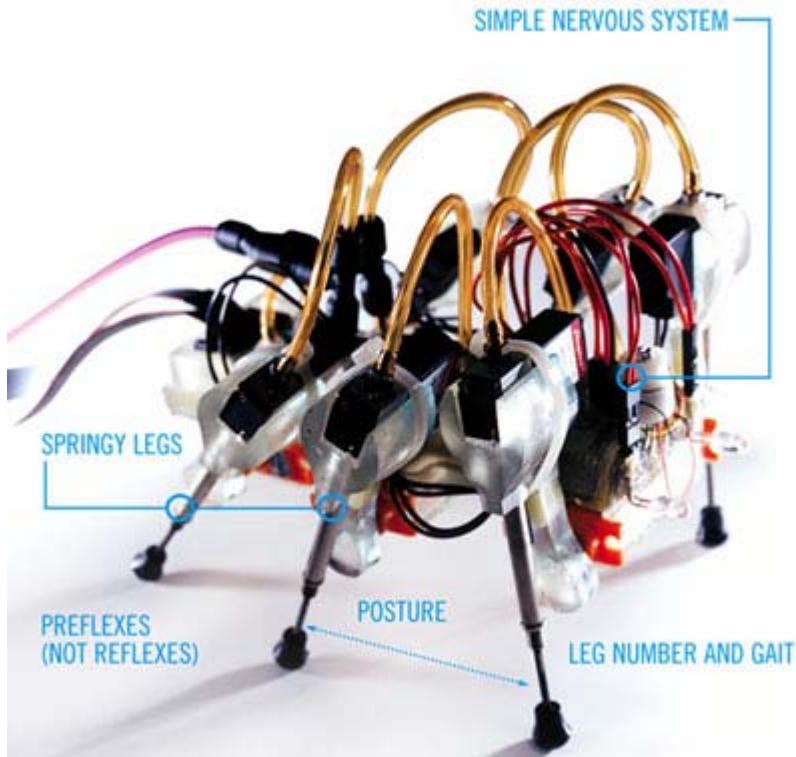


Stanford Report, March 12, 2003

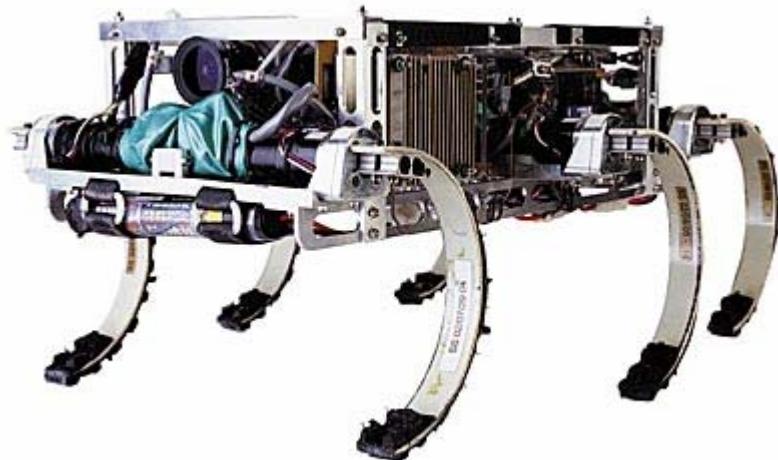
## Mimicking cockroaches' 'mechanical intelligence'

*Development of legged robots could help in navigating disaster sites, other dangerous and difficult-to-reach places*

BY BRONWYN BARNETT

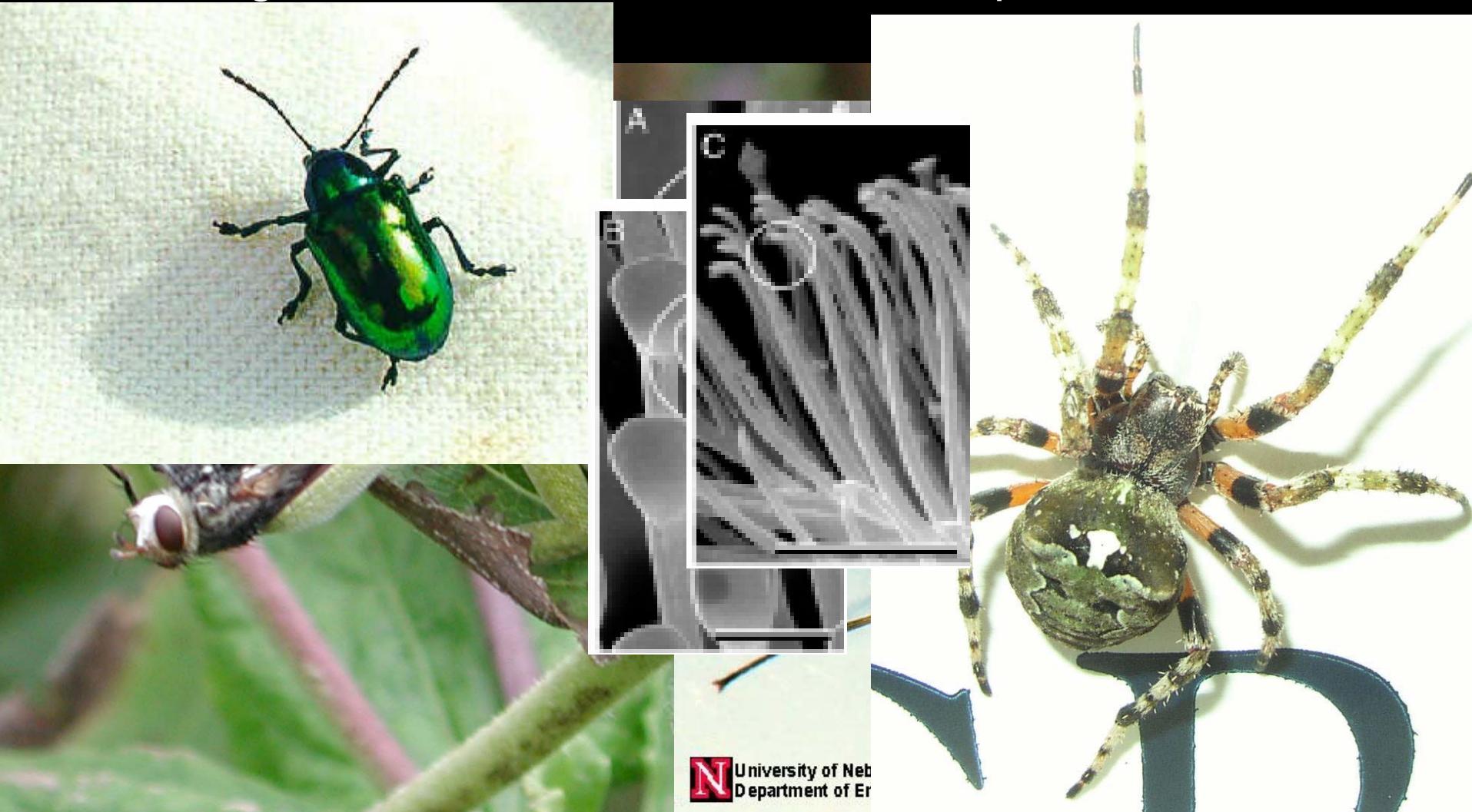


Mark Cutkosky



# “Fine hair” adhesive motif

- Also found in other lizards and insects
  - e.g. anoles, crickets, beetles, flies, spiders.



# Adhesion Mechanism



# van der Waals

Short range London Dispersion Force

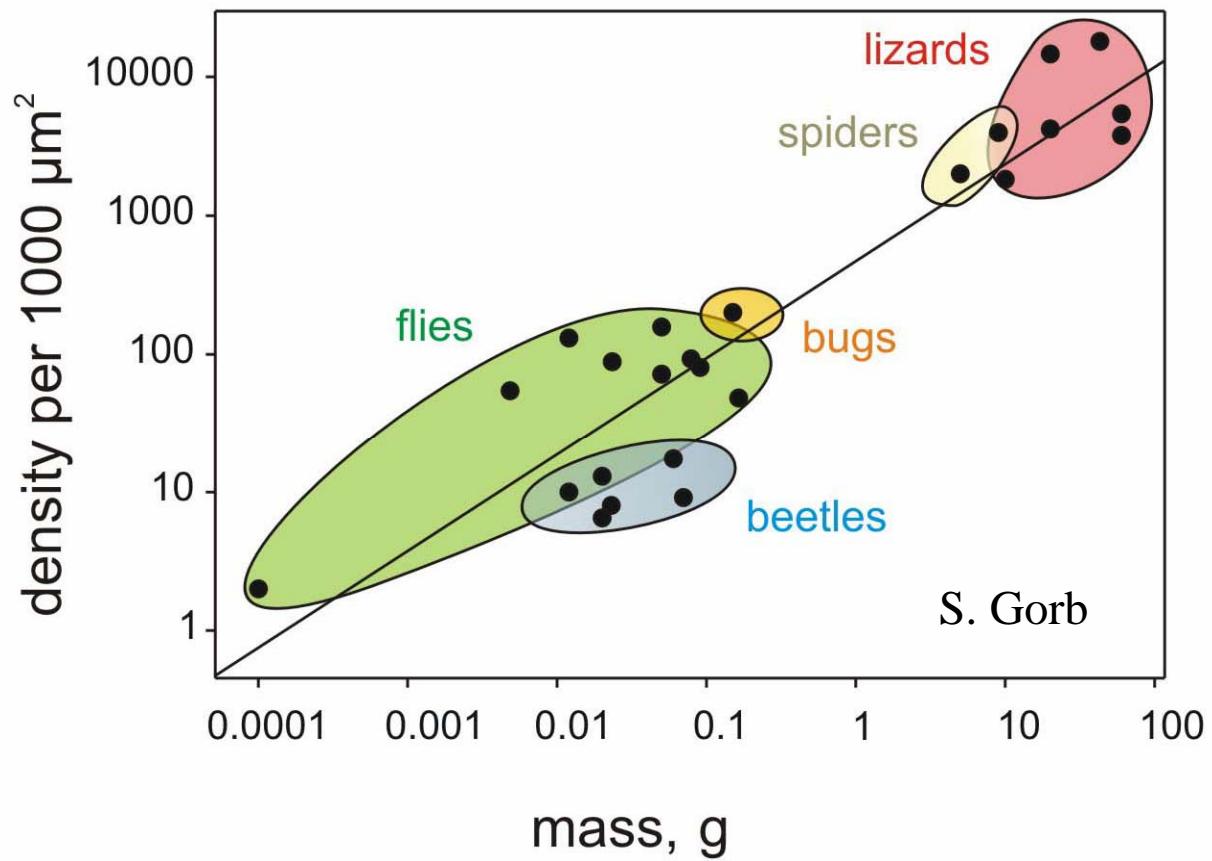
$$F = n H R / 6D^2$$

H = Hamaker Constant (surface property)

R = Radius

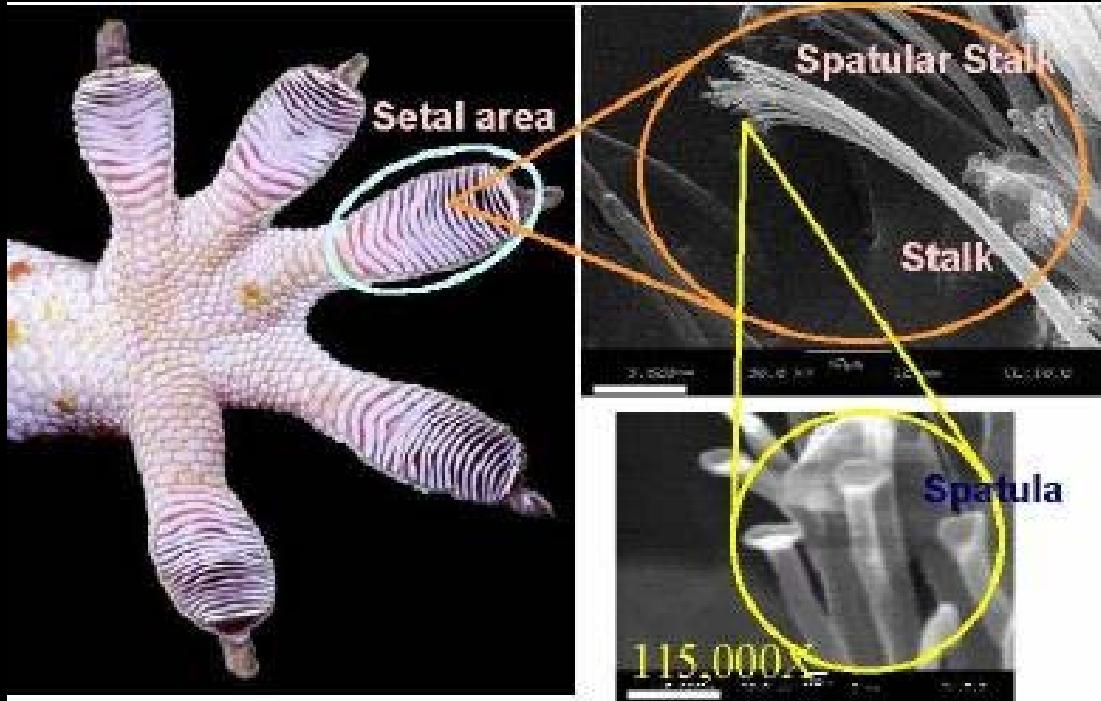
D = Cut-Off Distance (variable)

n = Number of Contacts

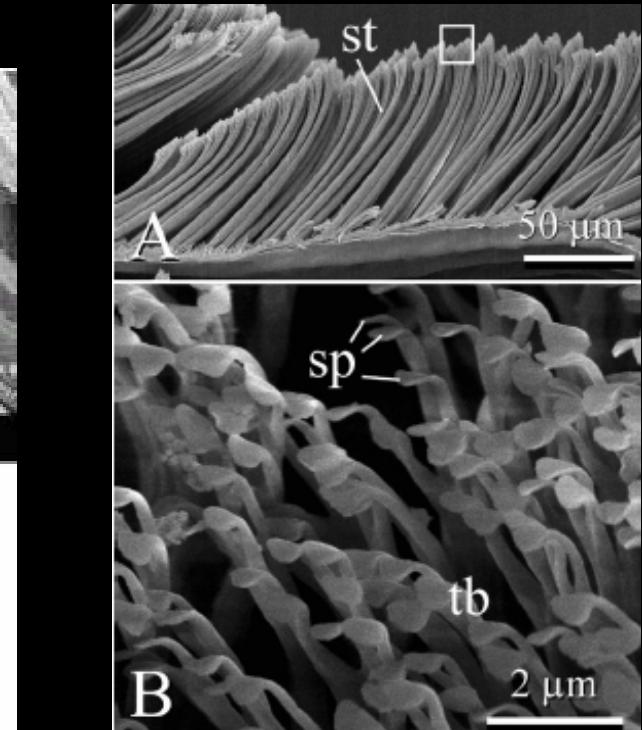


Arzt, Gorb, Spolenak PNAS 2003

# Multi-scale conformal structure



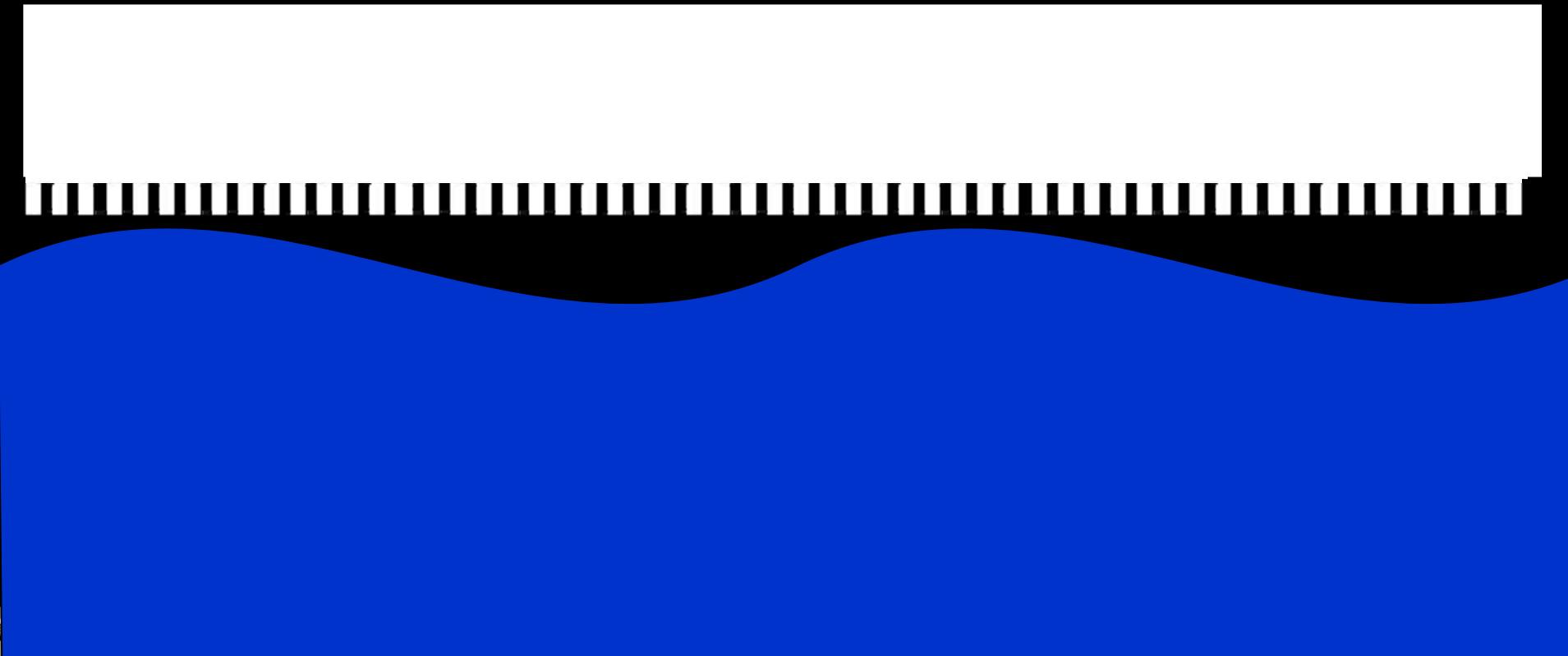
Autumn, K., et al., PNAS, 99(19): p. 12252-12256 (2002).



This hierarchical construction makes the lizard adhesive system elastically very soft on all relevant length scales (from mm to nm).

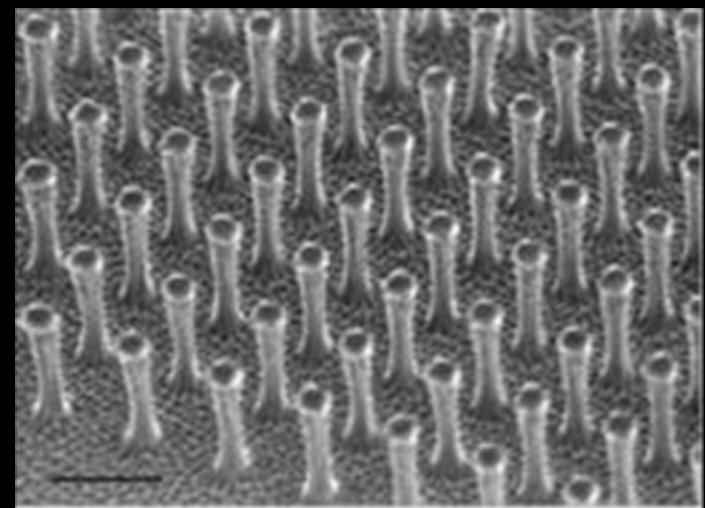
Persson and Gorb, J. Chem. Phys. (2003).

# Controllable Conformance



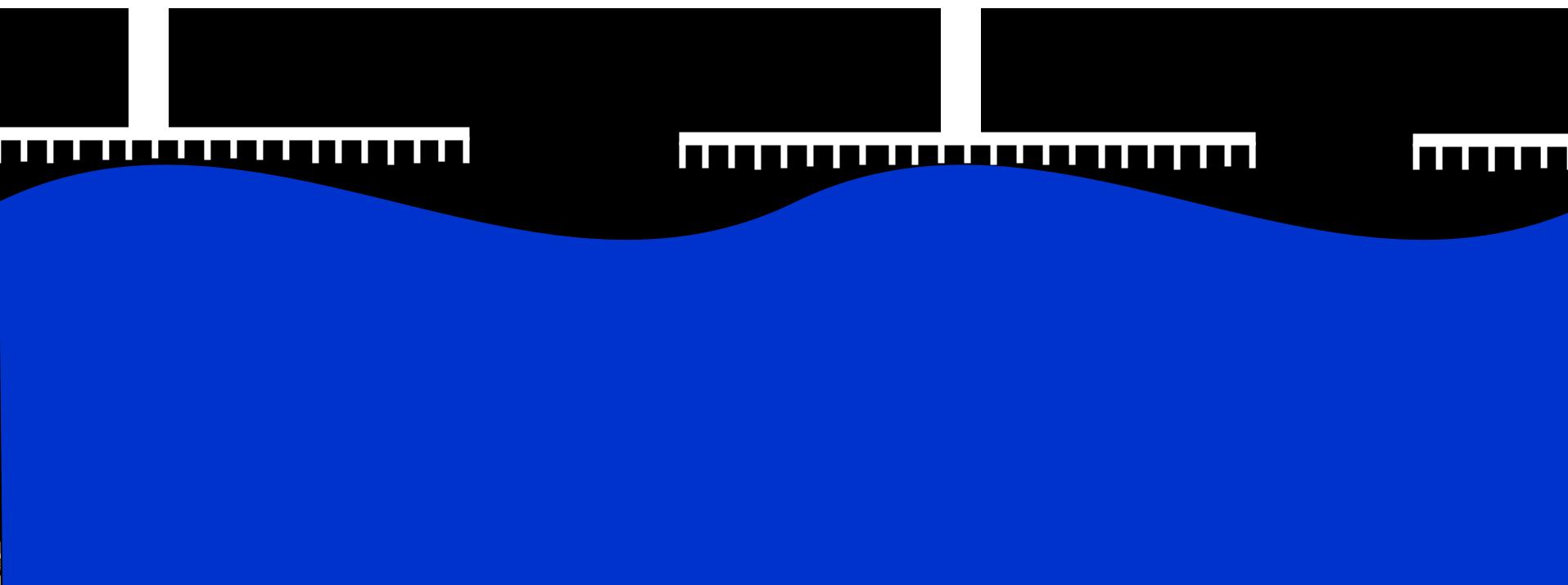


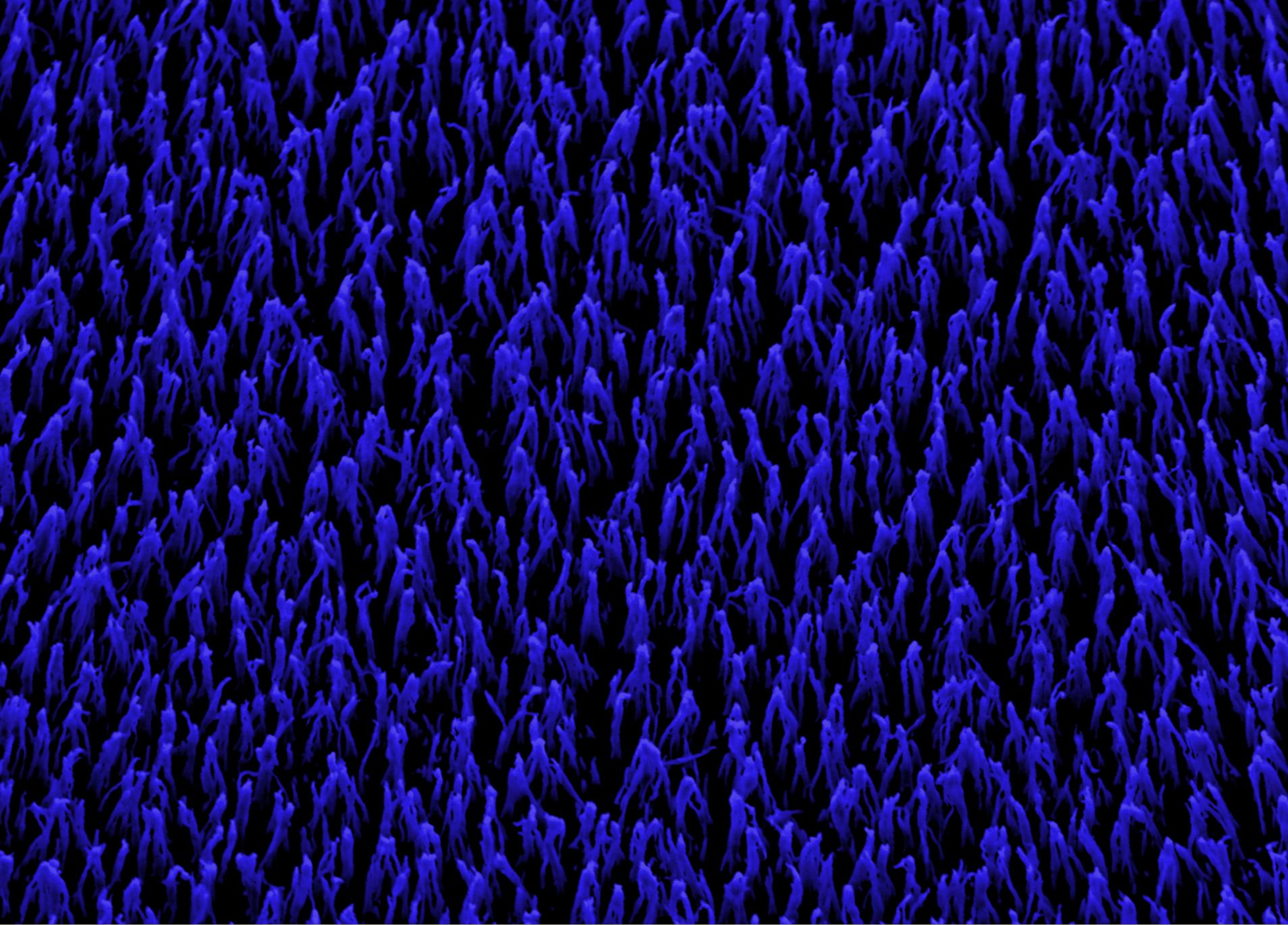
“The use of a soft rather than solid base has dramatically (by nearly 1,000 times) improved gecko tape to support the weight of a suitably light familiar object (a toy in Fig. 4).”



Geim, A. K., Dubonos, S. V.,  
Grigorieva, I. V., Novoselov, K. S. &  
Zhukov, A. A. *Nature Materials* **2**,  
461-463 (2003).

# Controllable Conformance





# Fabrication



## SHARPS PROCESS FLOW



Silicon Wafer



Oxidize



Photolithographic P Mask



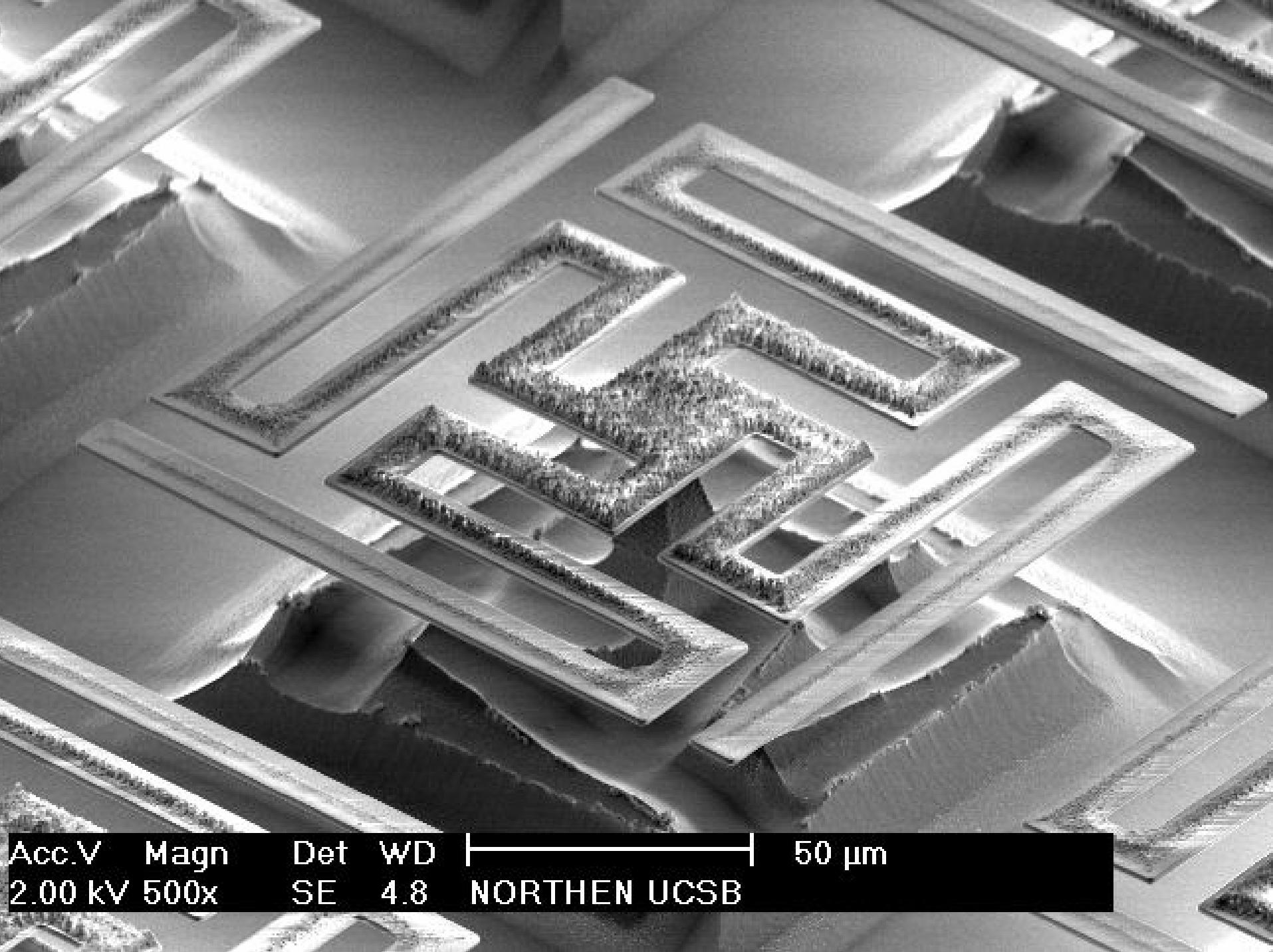
ICP Oxide Etch



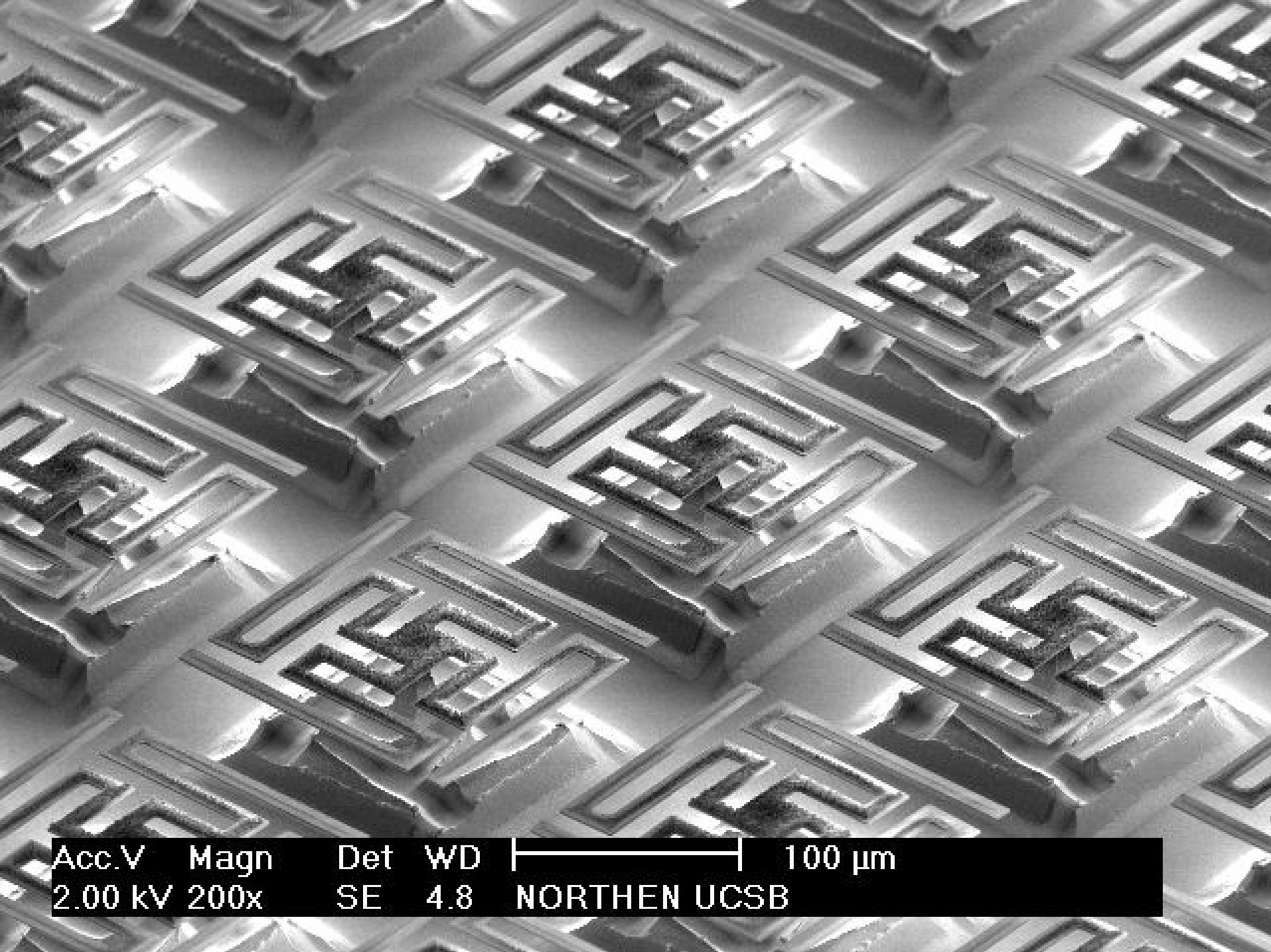
Bosch Deep Etch



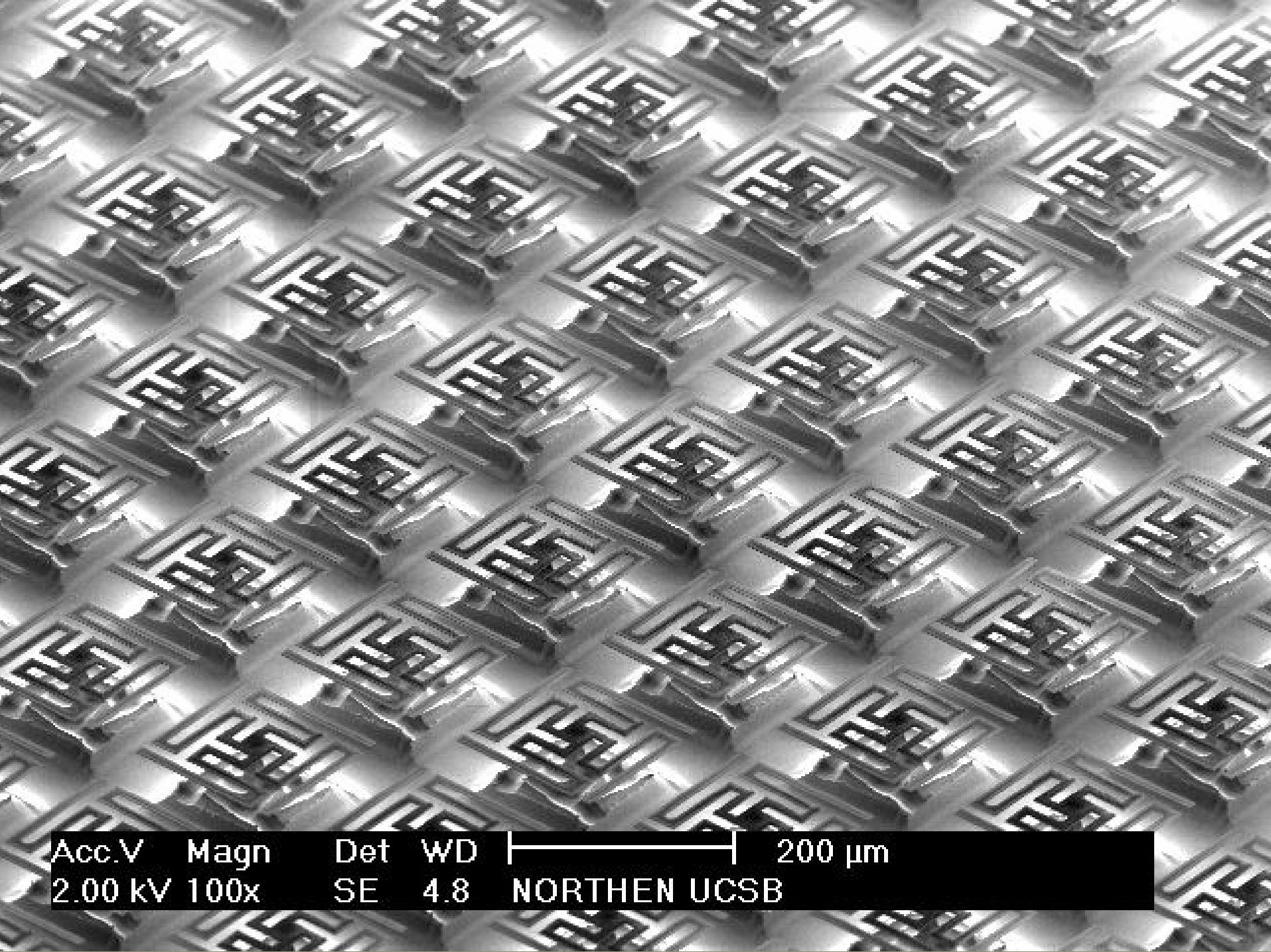
Extended Release



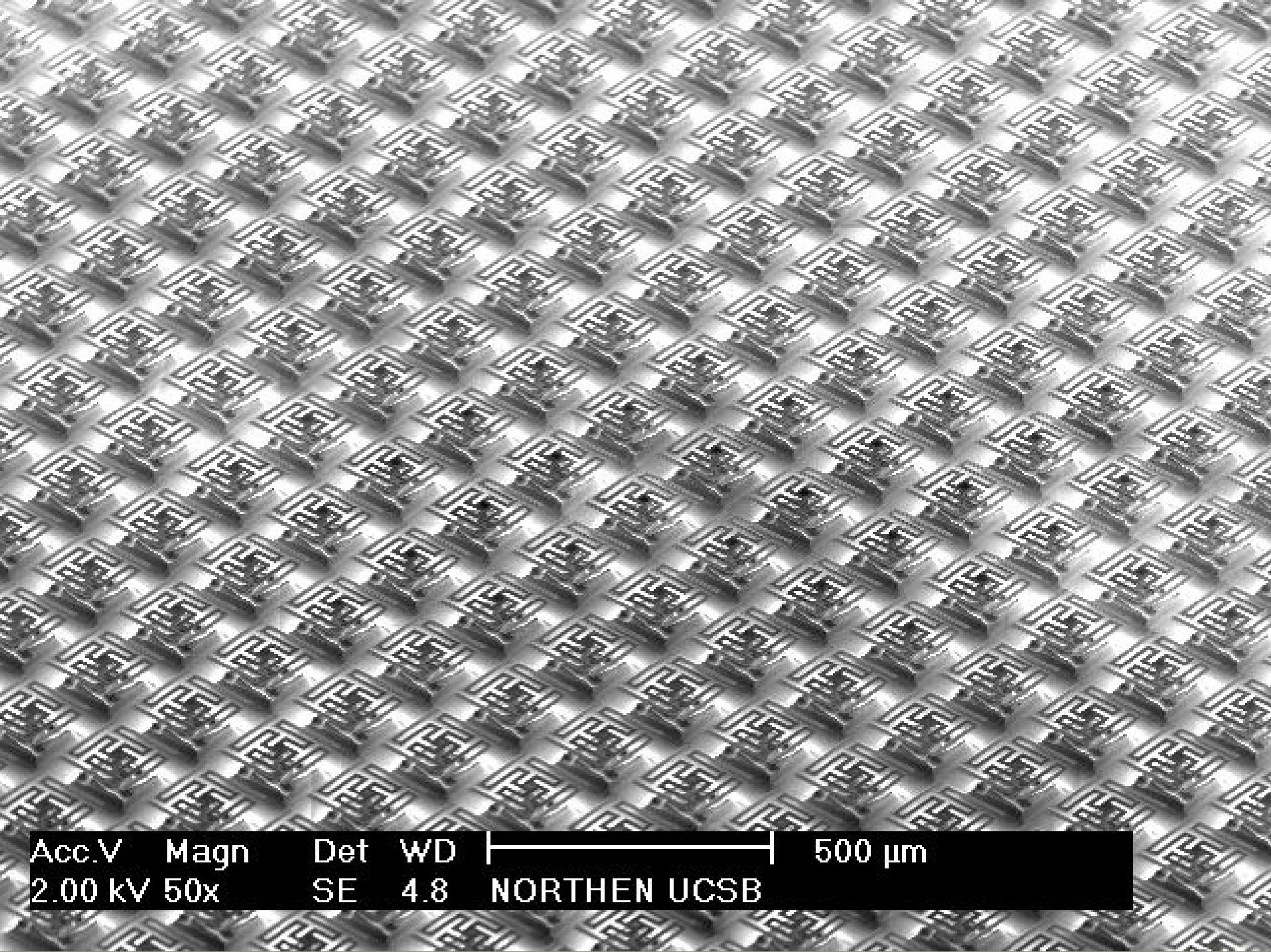
Acc.V    Magn    Det    WD    | 50 µm  
2.00 kV 500x    SE    4.8    NORTHEN UCSB



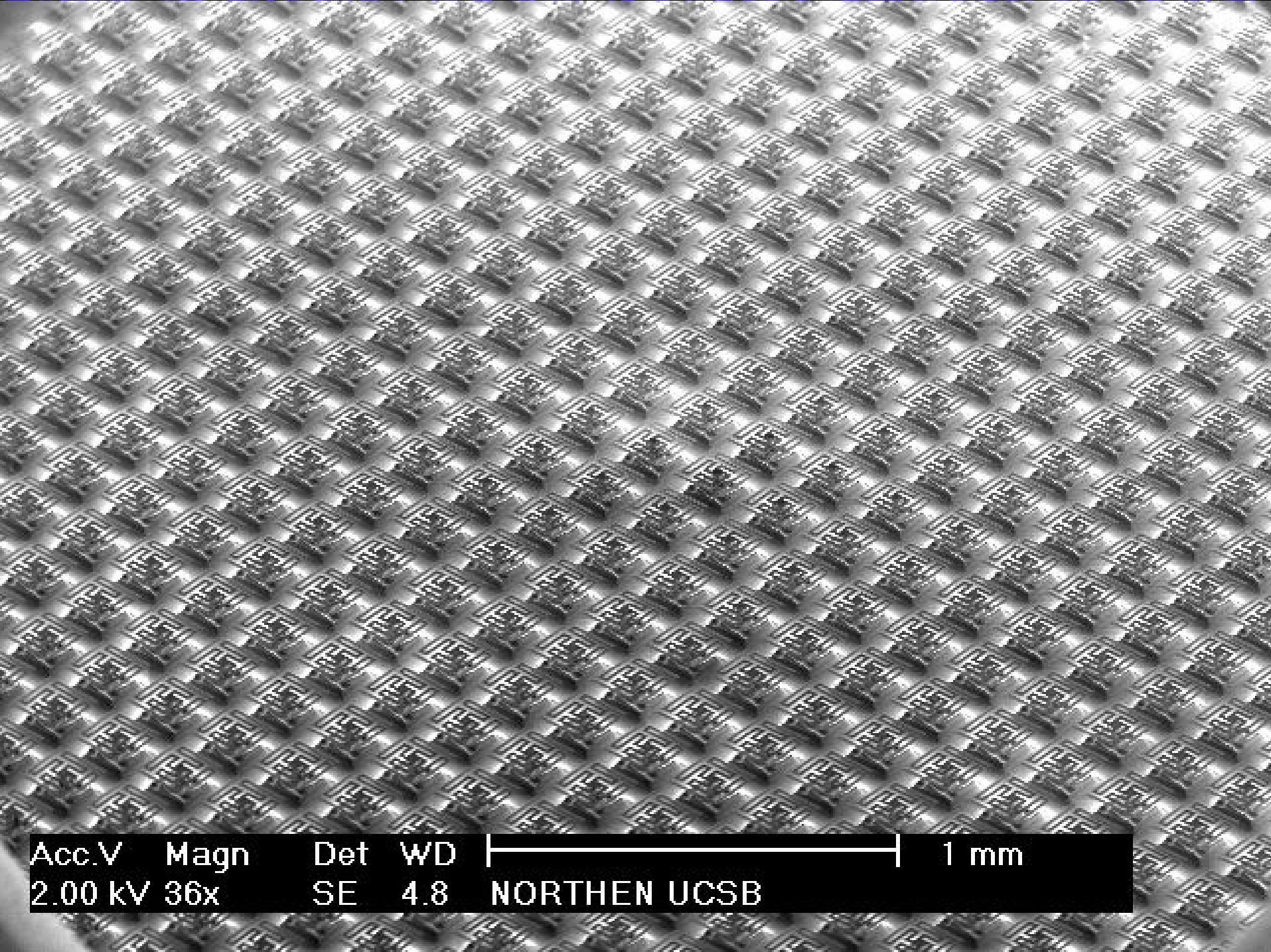
Acc.V Magn Det WD 100 µm  
2.00 KV 200x SE 4.8 NORTHEN UCSB



Acc.V Magn Det WD 200 µm  
2.00 kV 100x SE 4.8 NORTHEN UCSB

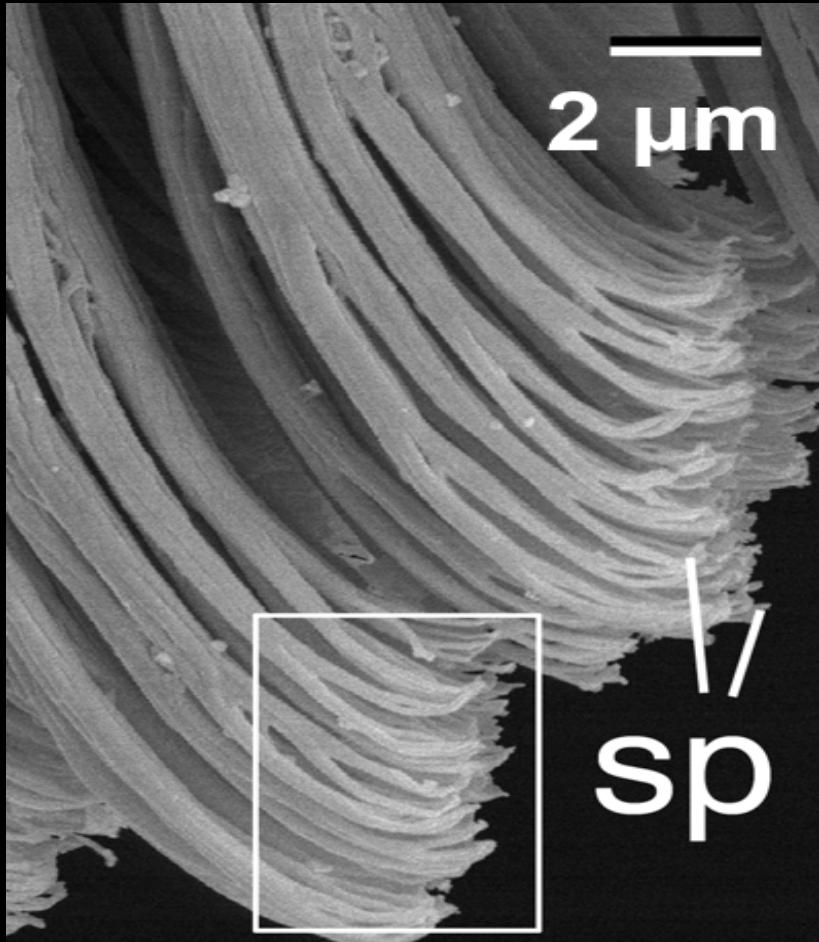


Acc.V Magn Det WD 500 μm  
2.00 kV 50x SE 4.8 NORTHEN UCSB



Acc.V Magn Det WD | 1 mm  
2.00 KV 36x SE 4.8 NORTHEN UCSB

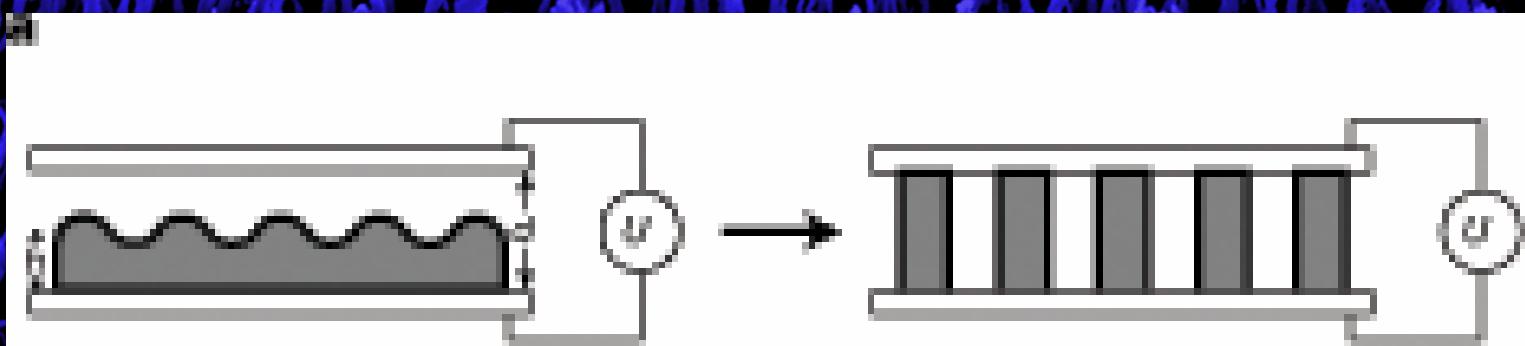
# Nanorod Properties



Courtesy Edward Arzt (S. Gorb)

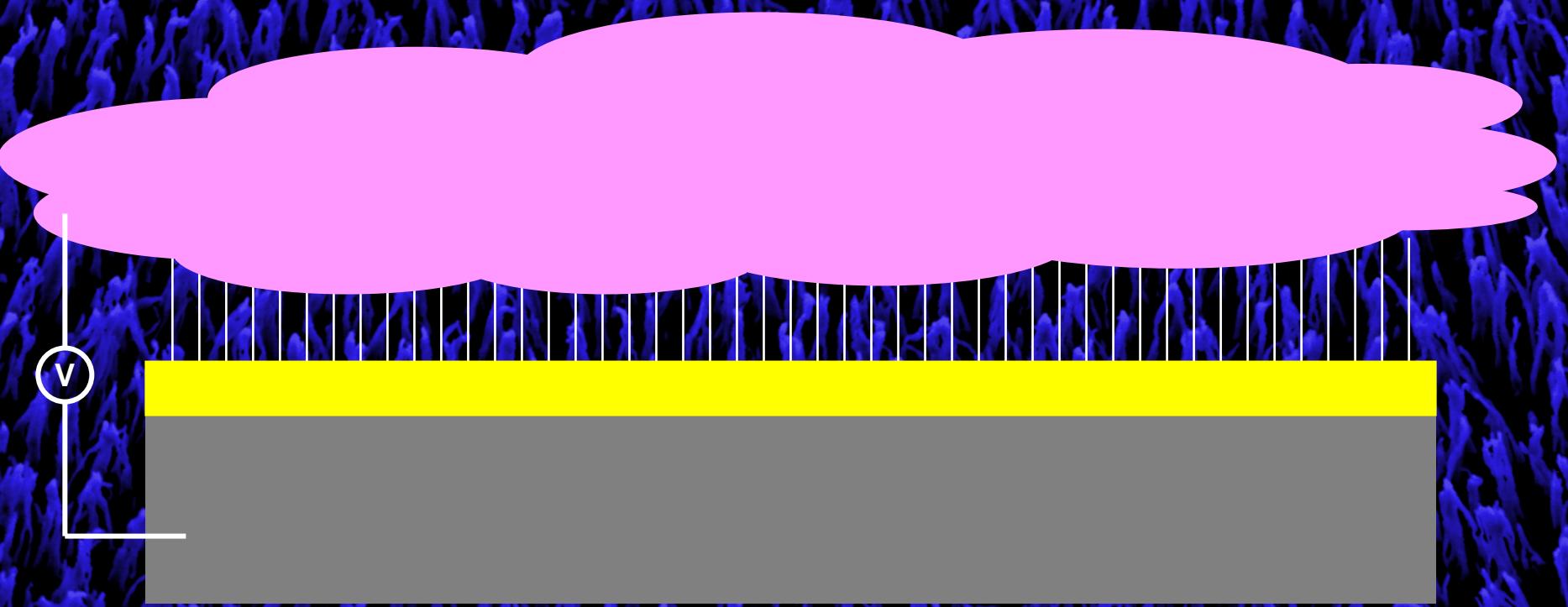
- Diameter ~ 200 nm
- Length ~ 4  $\mu$ m
- Beta Keratin
- Modulus ~ 1-15 GPa
- High Density
- No Condensation
- Ultra-Hydrophobic,  
Contact Angle ~170°

# Growing Nanorods

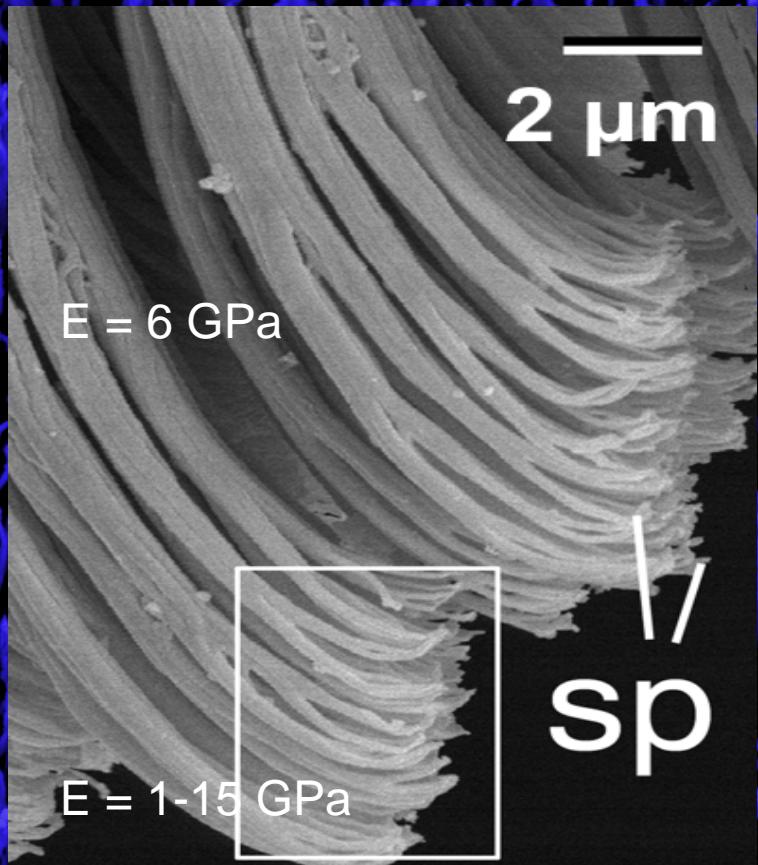
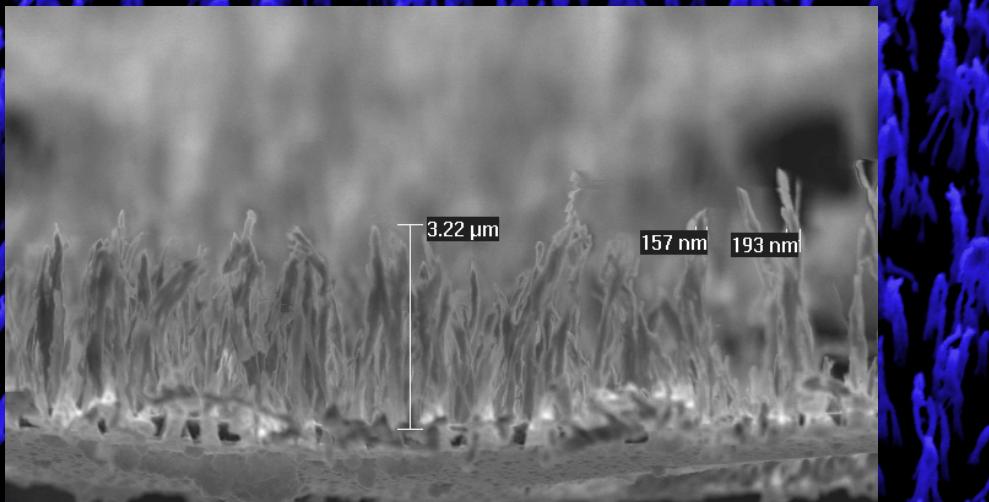


A. Schäffer, J. M. Alcolea, T. Weiss, T. Stein, ..., *Nature* 403, 774 (2000)

# Nanowire Synthesis

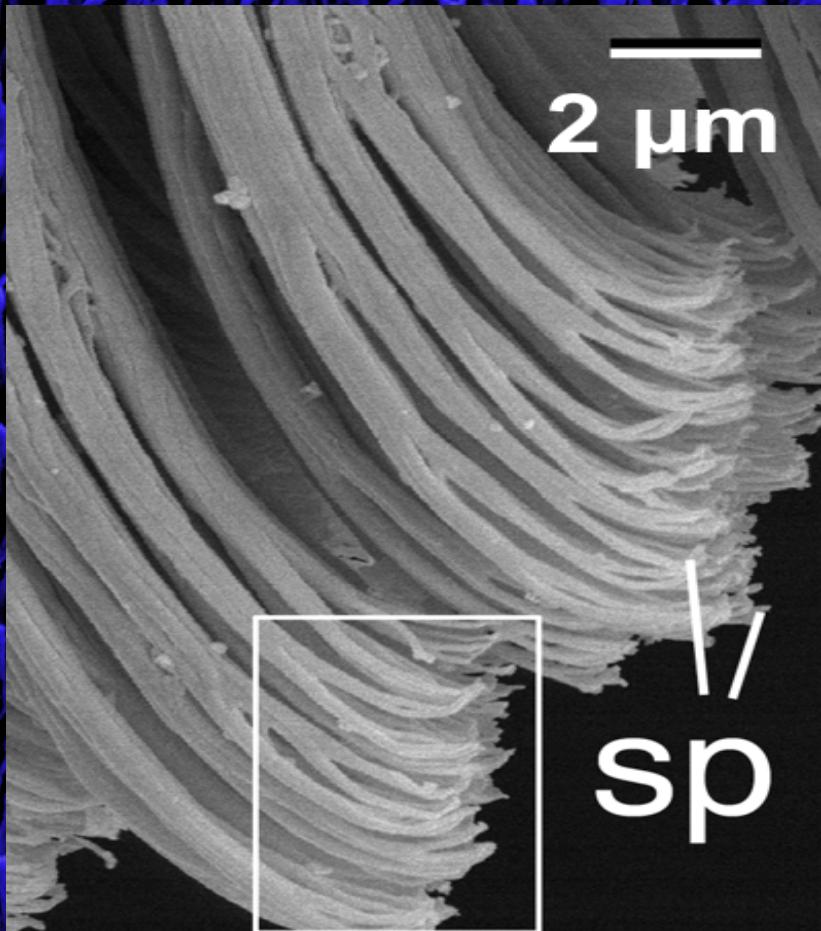


# 'Organorods'



Courtesy Edward Arzt (S. Gorb)

# Nanorod Properties



- Diameter ~ 200 nm
- Length ~ 4 μm
- Beta Keratin
- Modulus ~ 1-15 GPa
- High Density
- No Condensation
- Ultra-Hydrophobic,  
Contact Angle ~170°

# Contact Angle

Hydrophilic

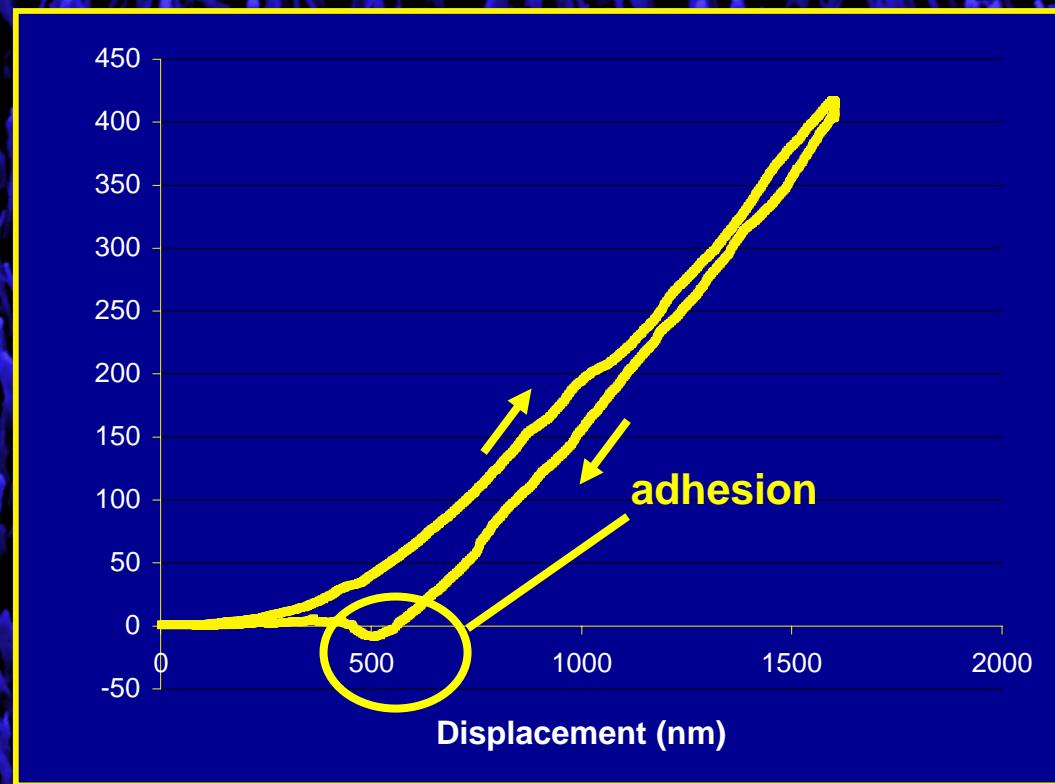
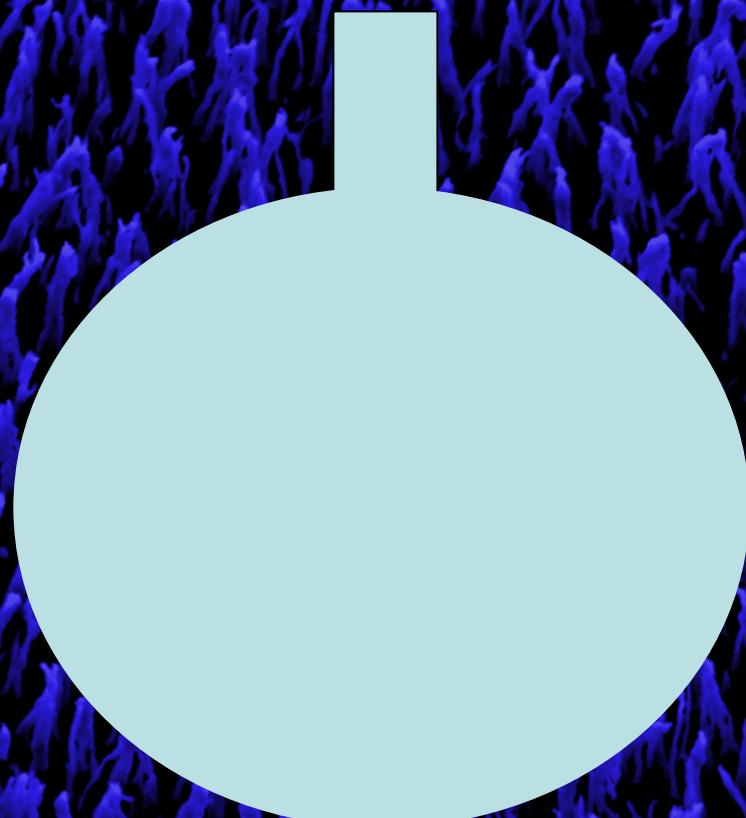
→ 42.5°

-OR-

Highly Hydrophobic → 145°



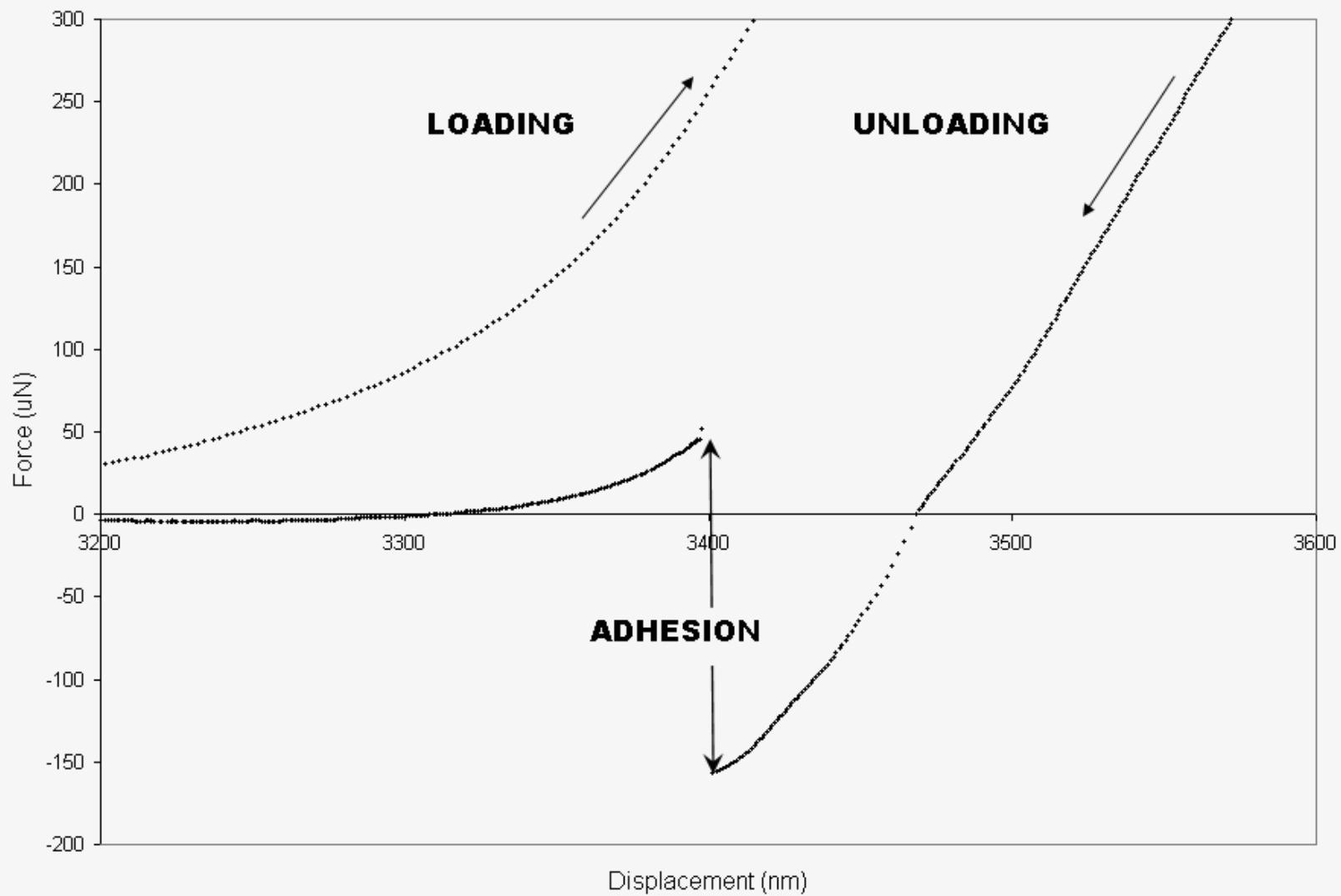
# Adhesion Testing



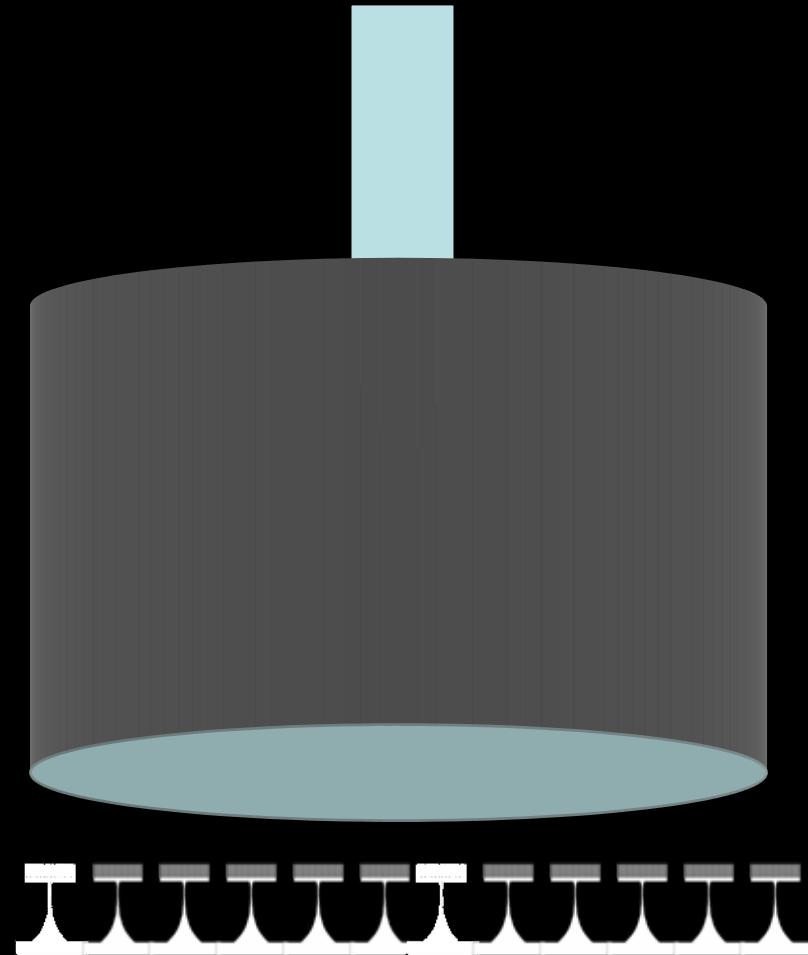
Northen, M. T., Turner, K.L. (2005). "Meso-scale adhesion testing of integrated micro- and nano-scale structures." Sensors and Actuators A (In Press).

Turner and Northen

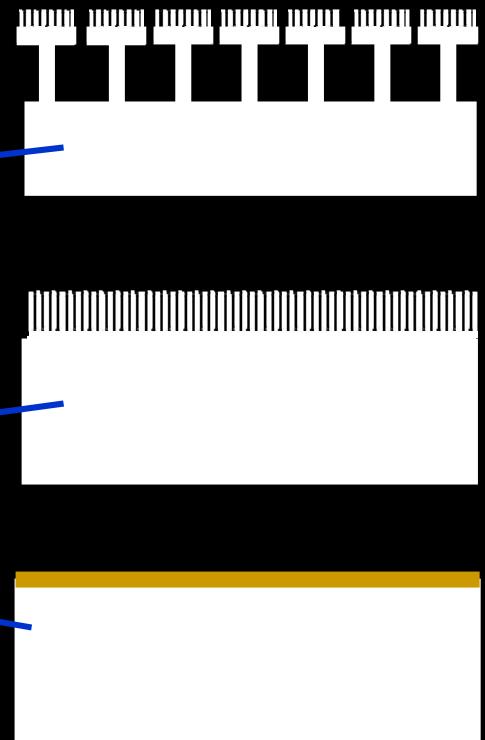
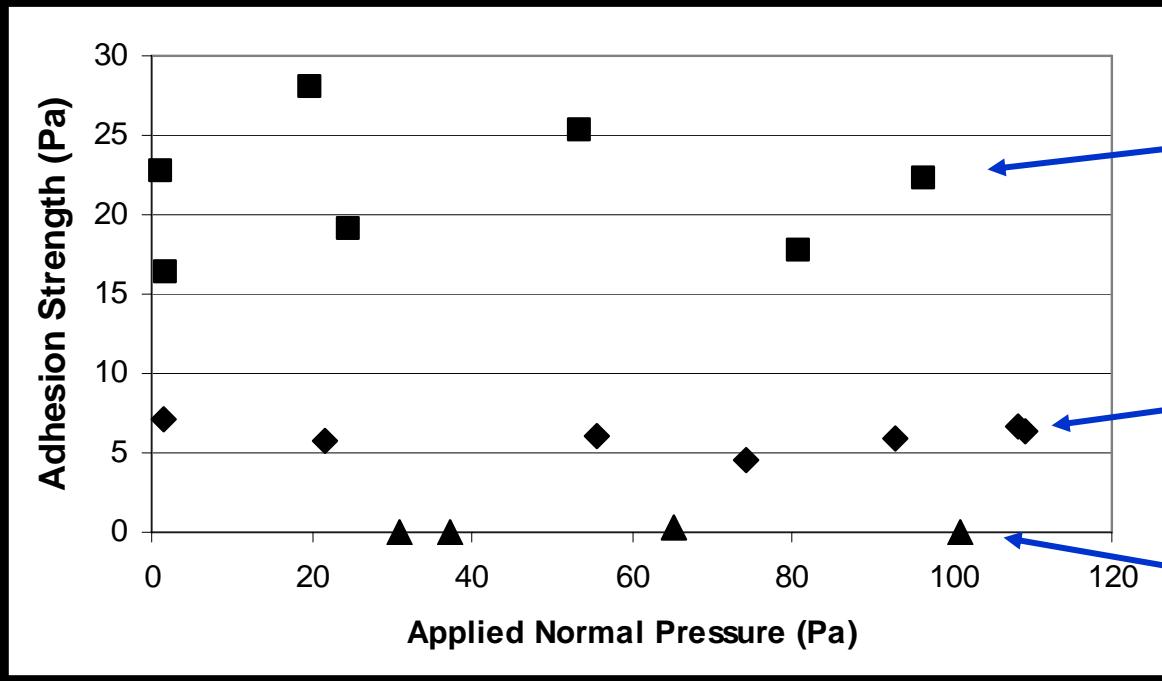
UCSB  
ICB



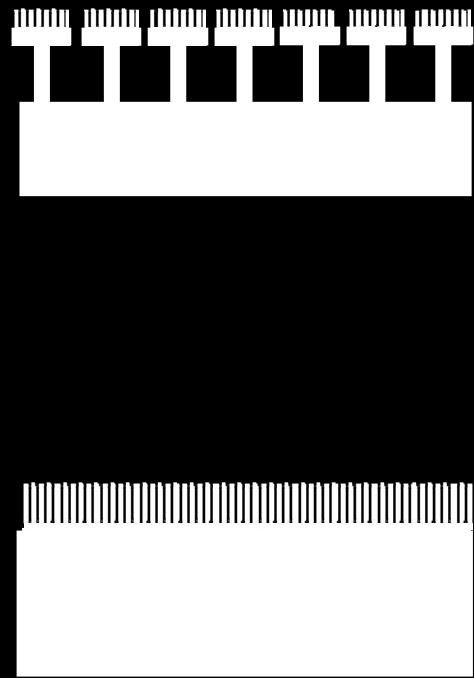
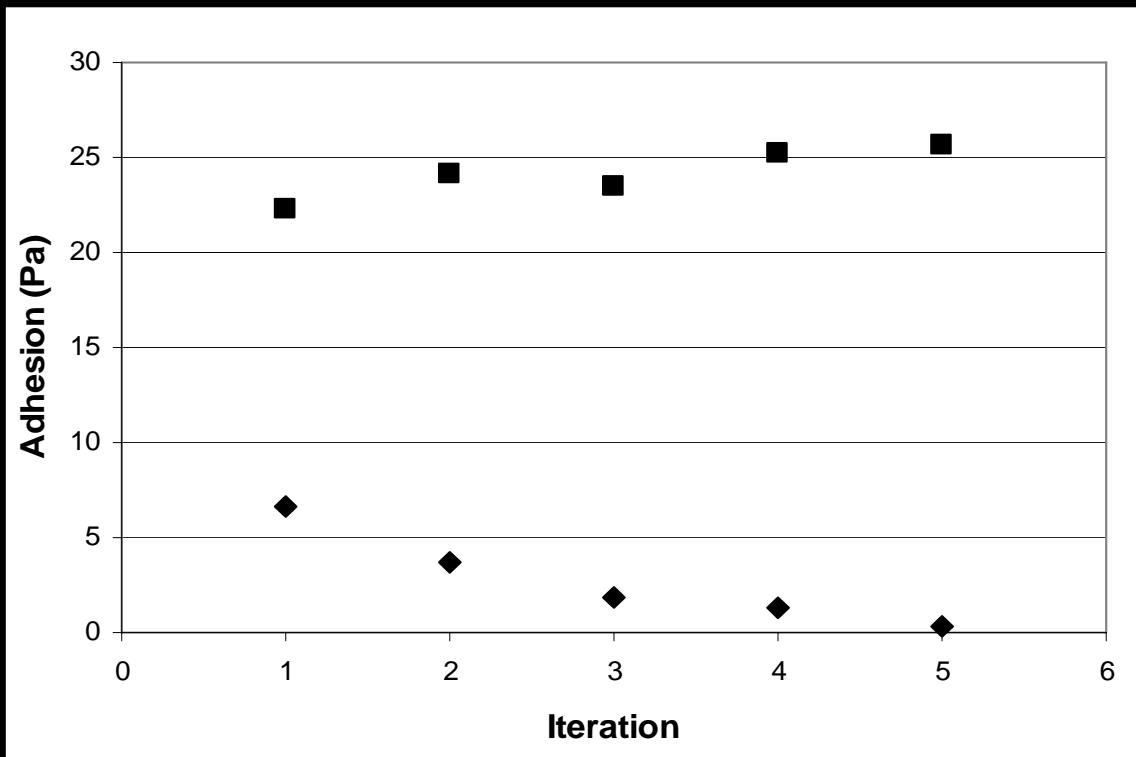
# Adhesion Testing



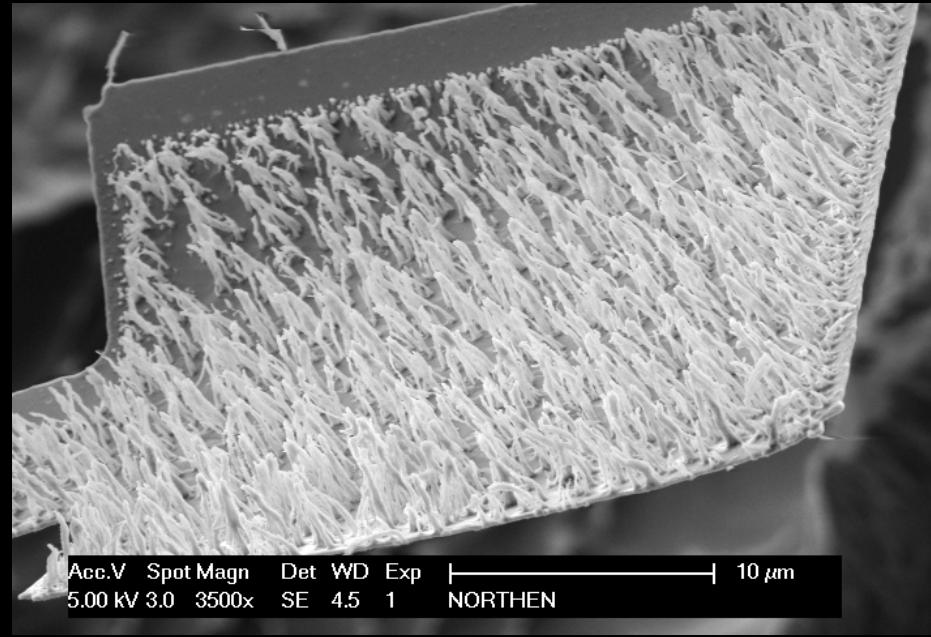
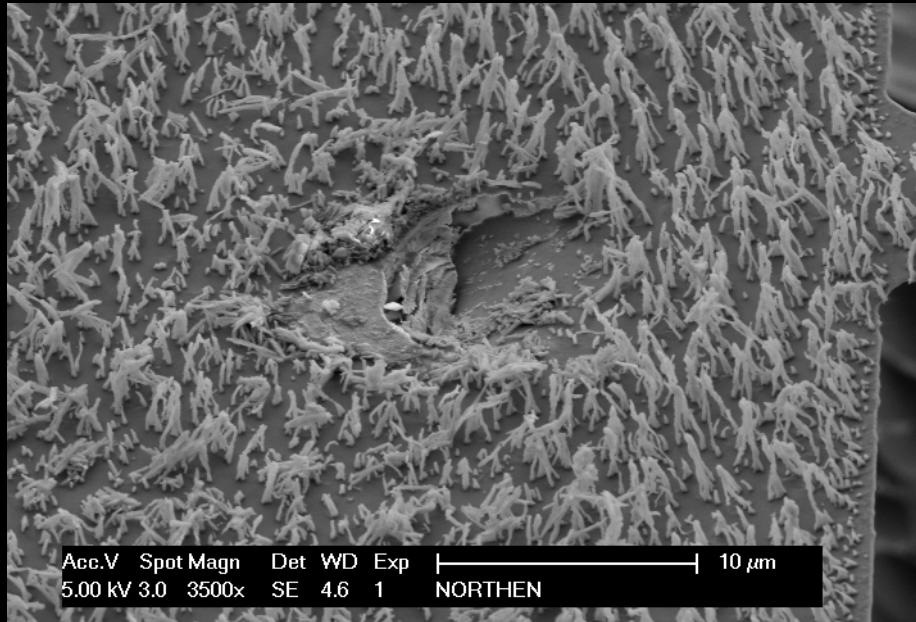
# Adhesion Comparison



# Durability Comparison

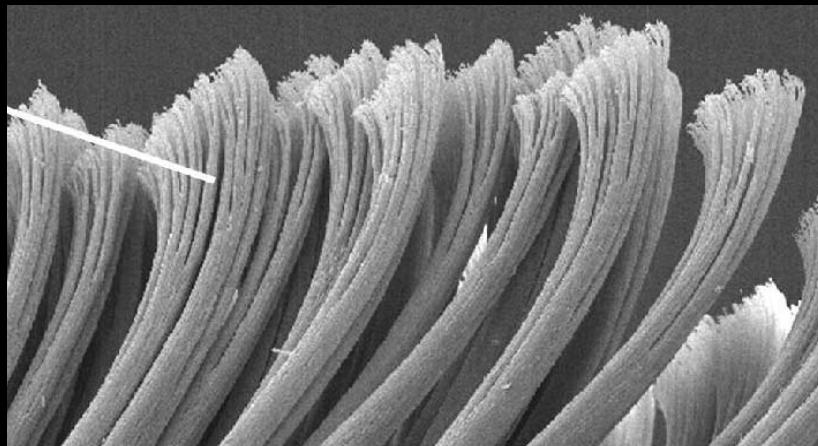


# Solid vs. Flexible

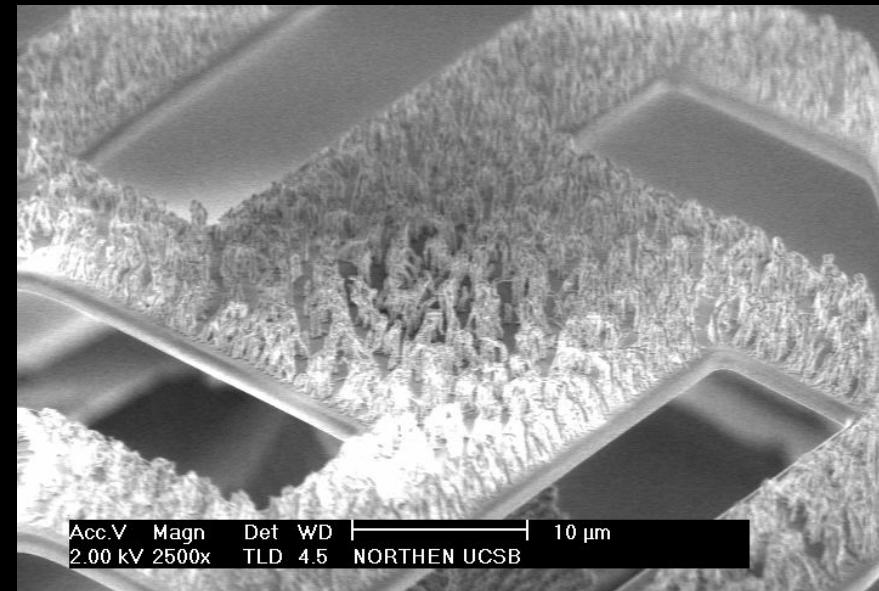


# Damage vs. No Damage

# Mimicked?



Courtesy Eduard Arzt (S. Gorb)



Acc.V Magn Det WD 10 μm  
2.00 kV 2500x TLD 4.5 NORTHEN UCSB

Gecko > 300 Pa (Adhesion)

90 kPa (Frictional Adhesion)

Synthetic < 30 Pa (Adhesion)

$$\mu' = F_{\text{adhesion}} / F_{\text{preload}}$$

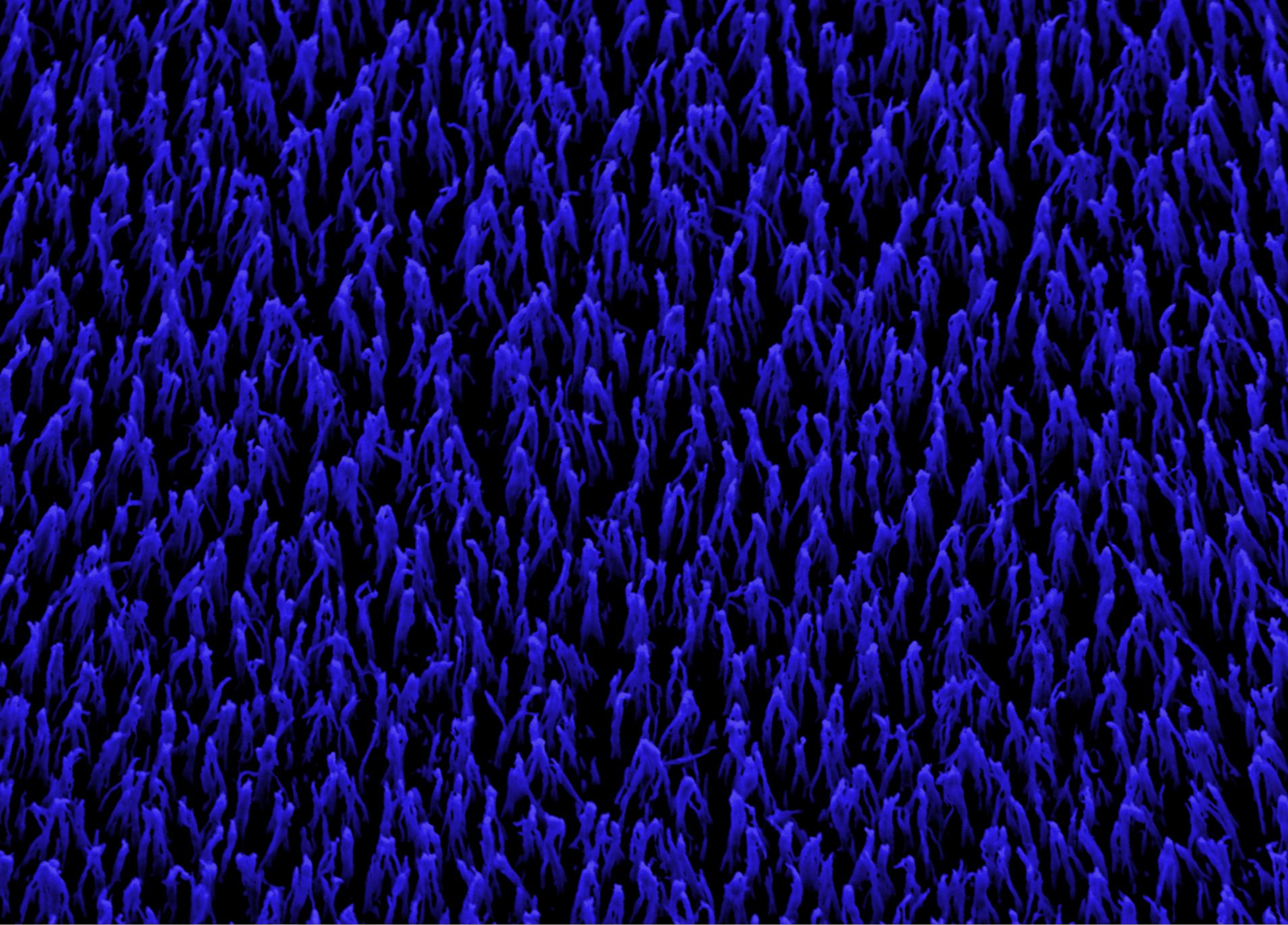
Geim et. al →  $\mu' = 0.06$

Northen & Turner →  $\mu' = 0.125$

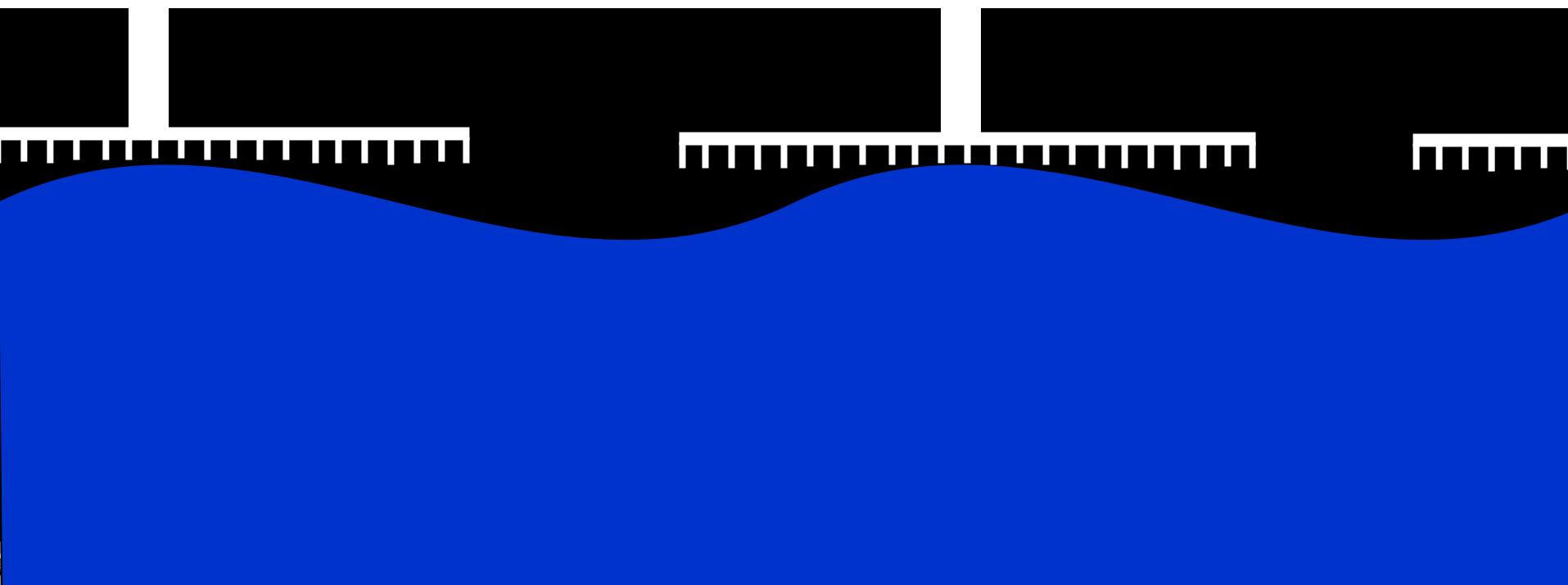
Gecko →  $\mu' = 8-15$

# Adhesion Control

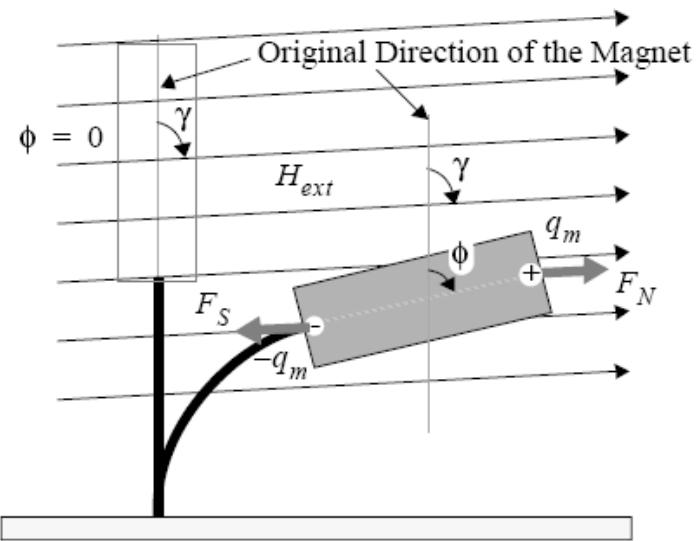




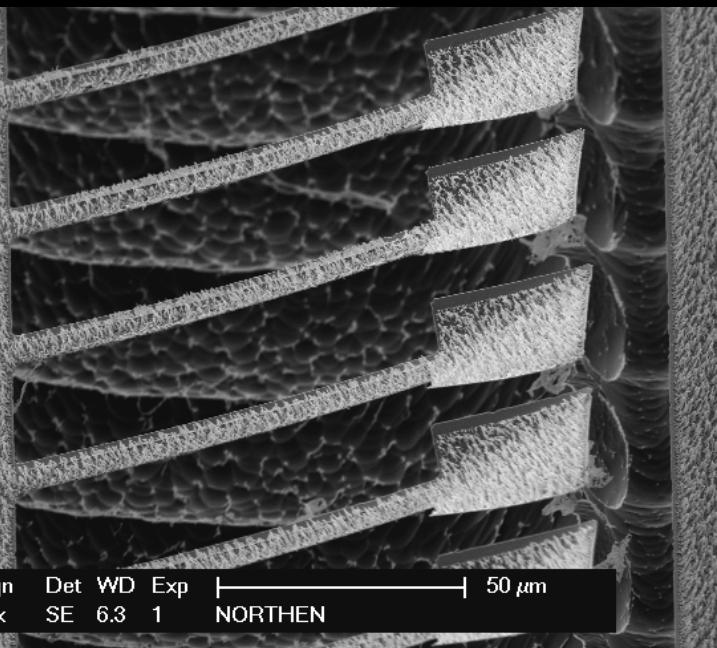
# Controllable Conformance



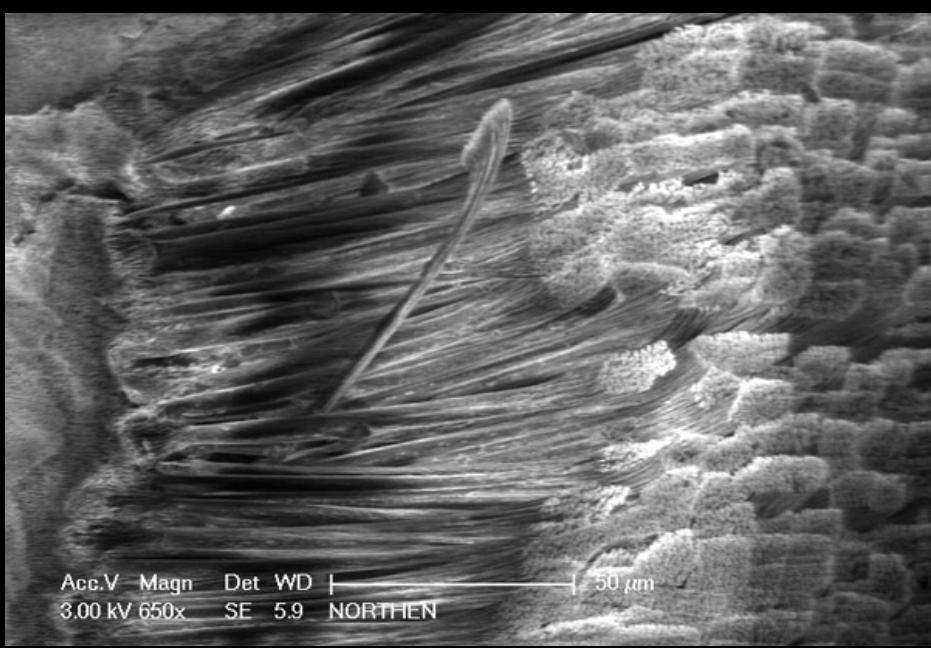
# Ferromagnet in a magnetic field



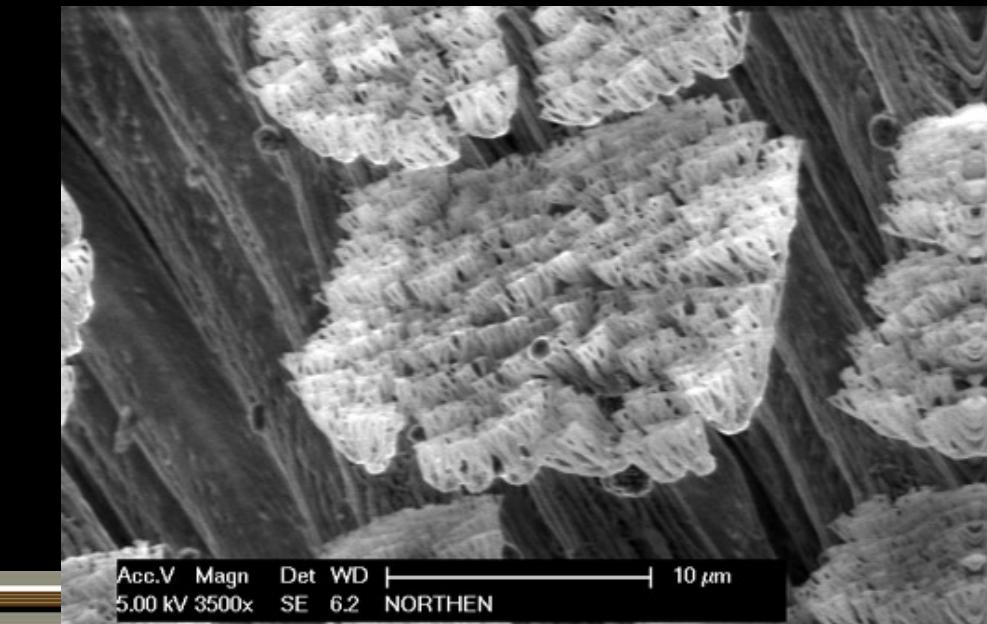
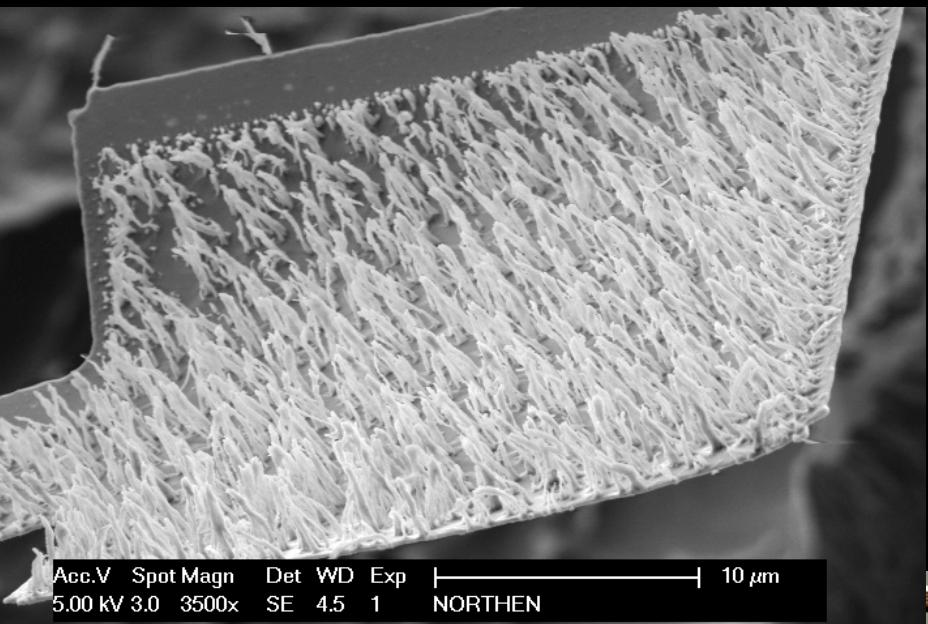
J. W. JUDY ET AL.: MAGNETIC MICROACTUATION OF POLYSILICON FLEXURE STRUCTURES.

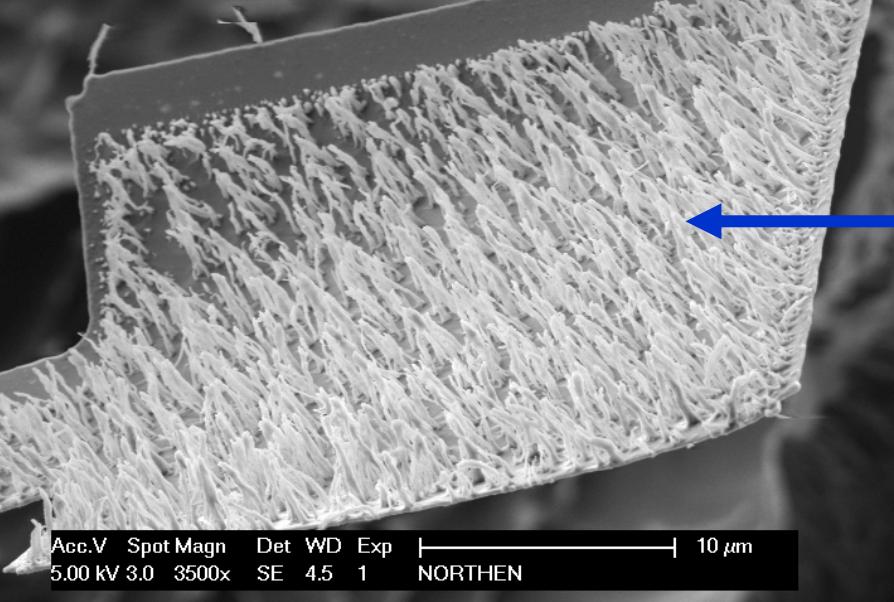


Michael-Fabricated



Gecko-Fabricated

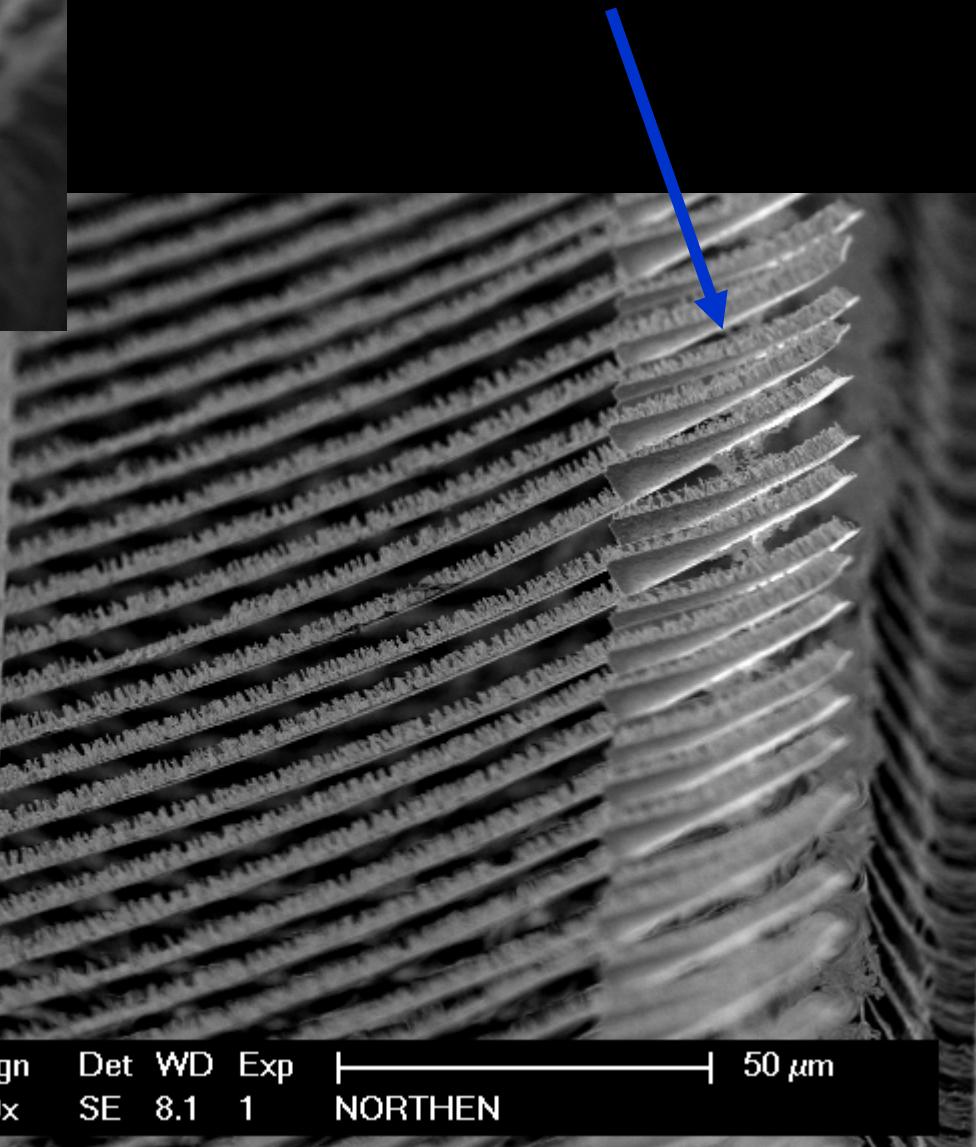




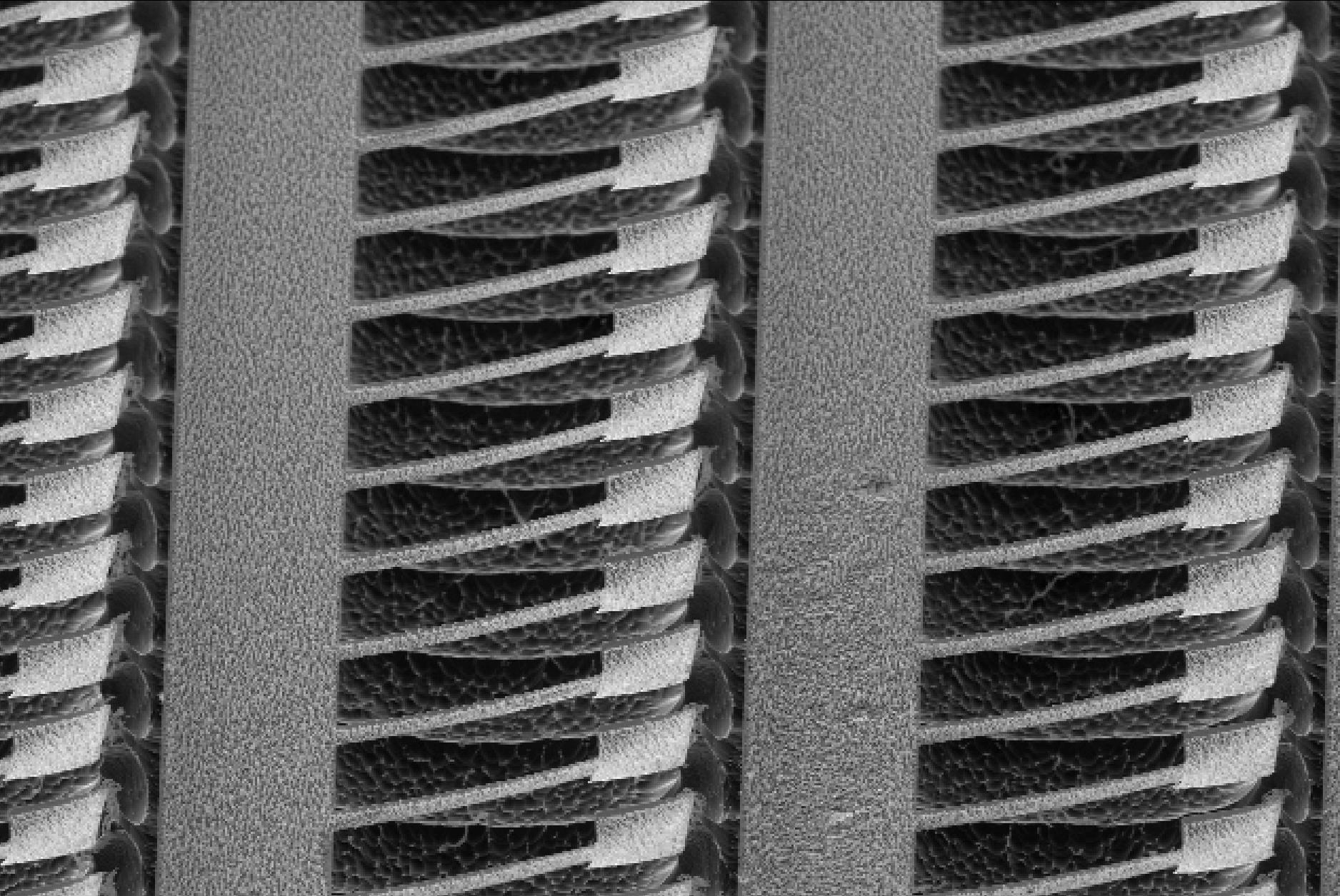
Active Area

Acc.V Spot Magn Det WD Exp | 10 μm  
5.00 kV 3.0 3500x SE 4.5 1 NORTHEN

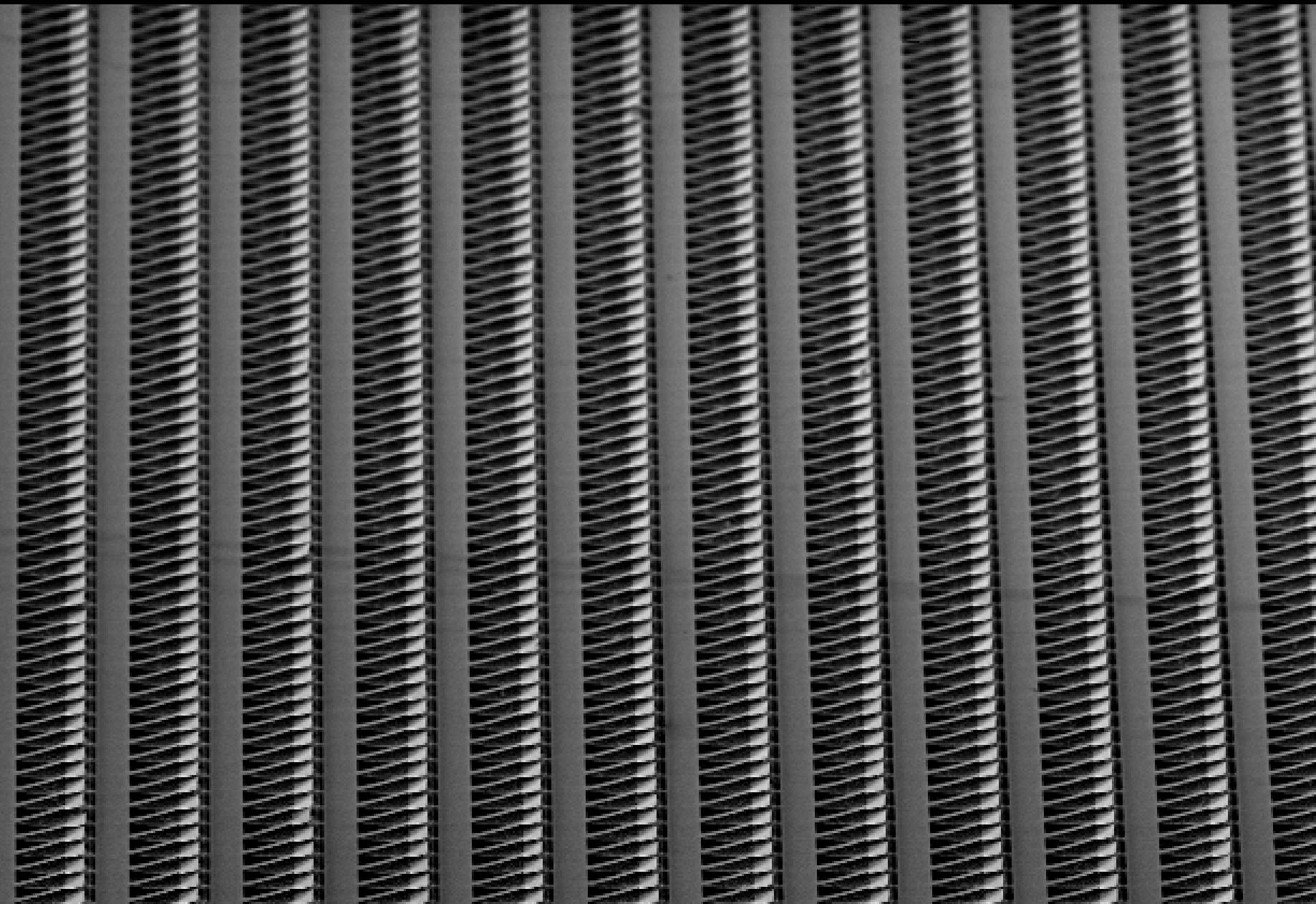
Support  
Substrate



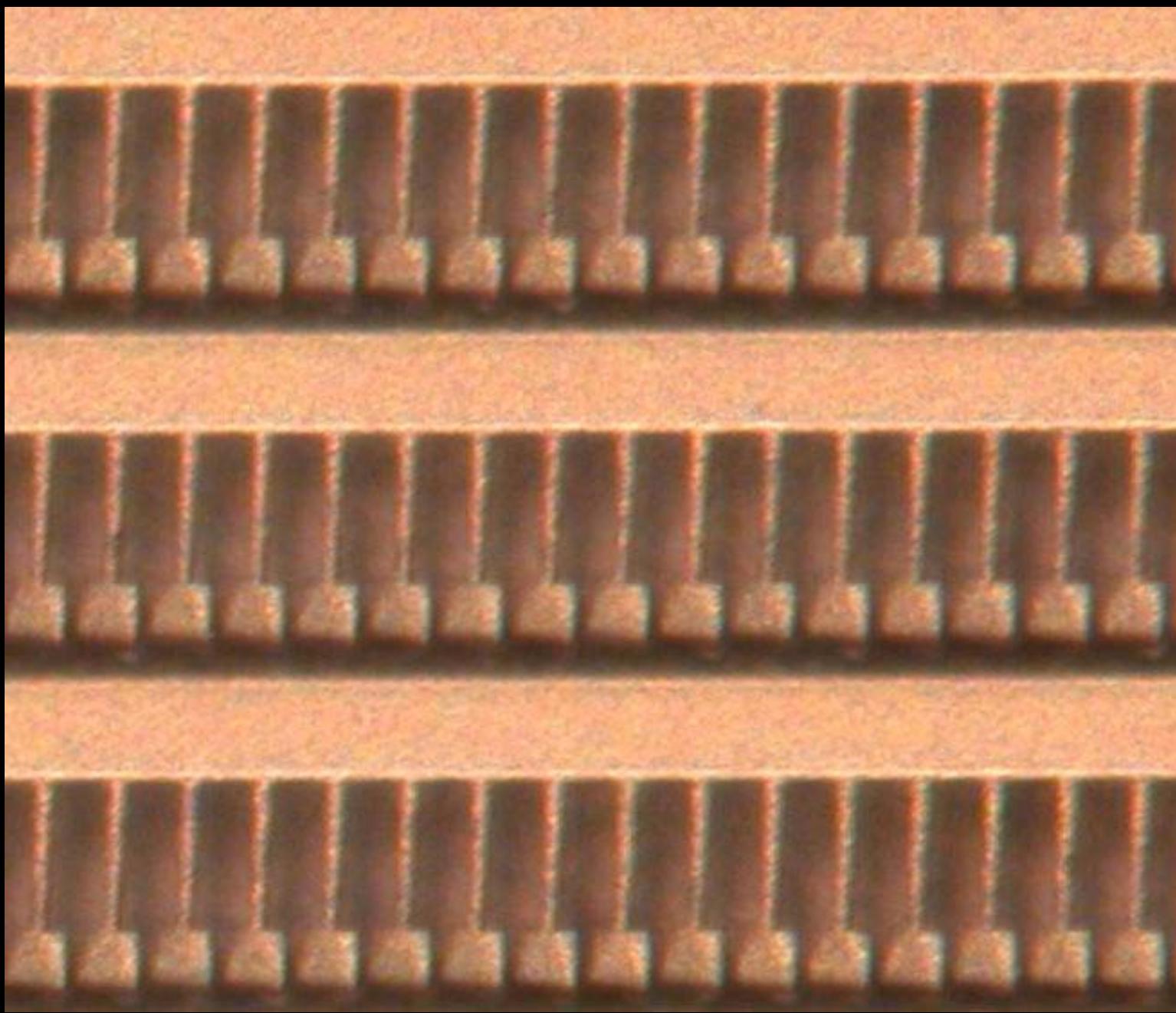
Acc.V Spot Magn Det WD Exp | 50 μm  
5.00 kV 3.0 650x SE 8.1 1 NORTHEN

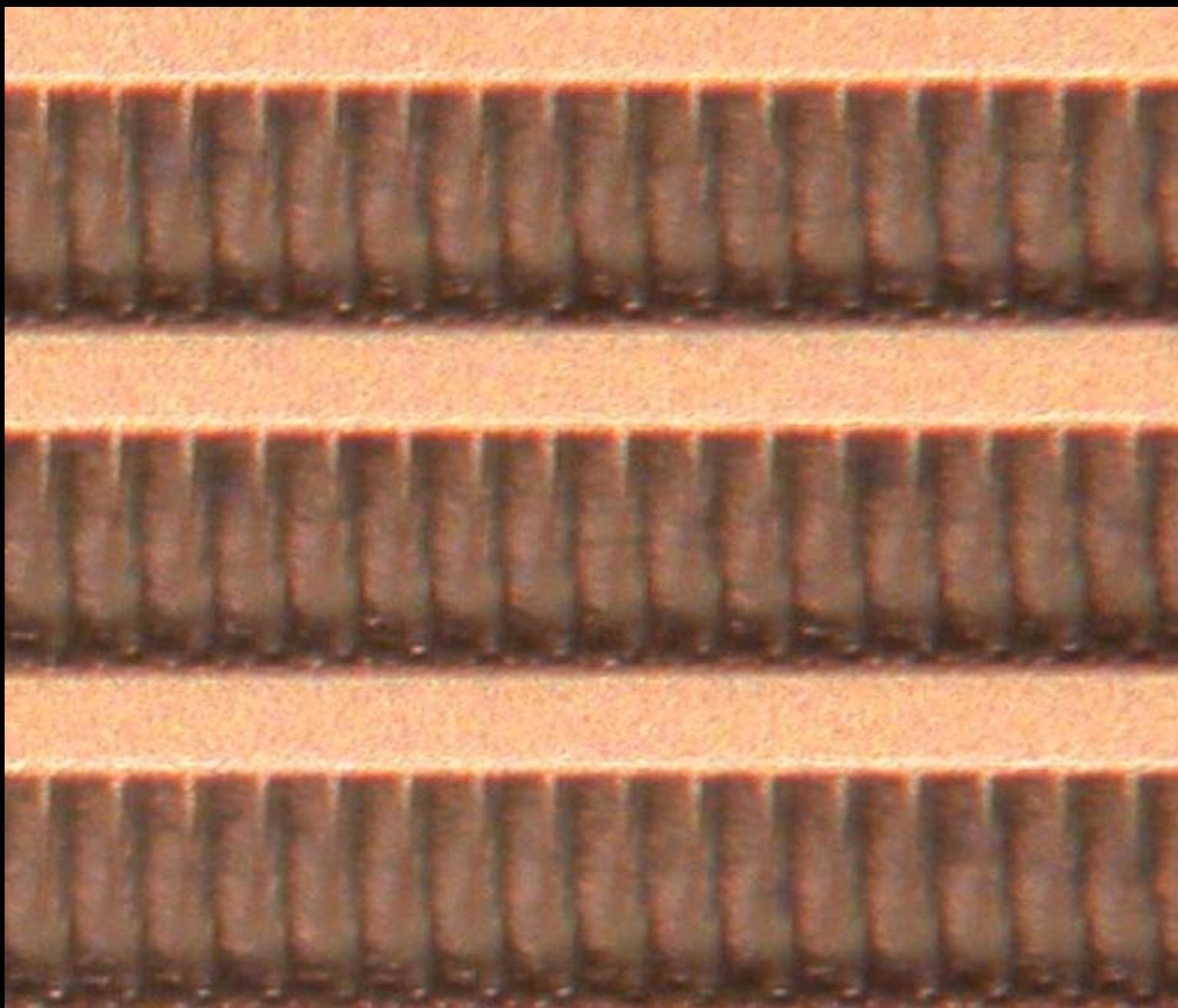


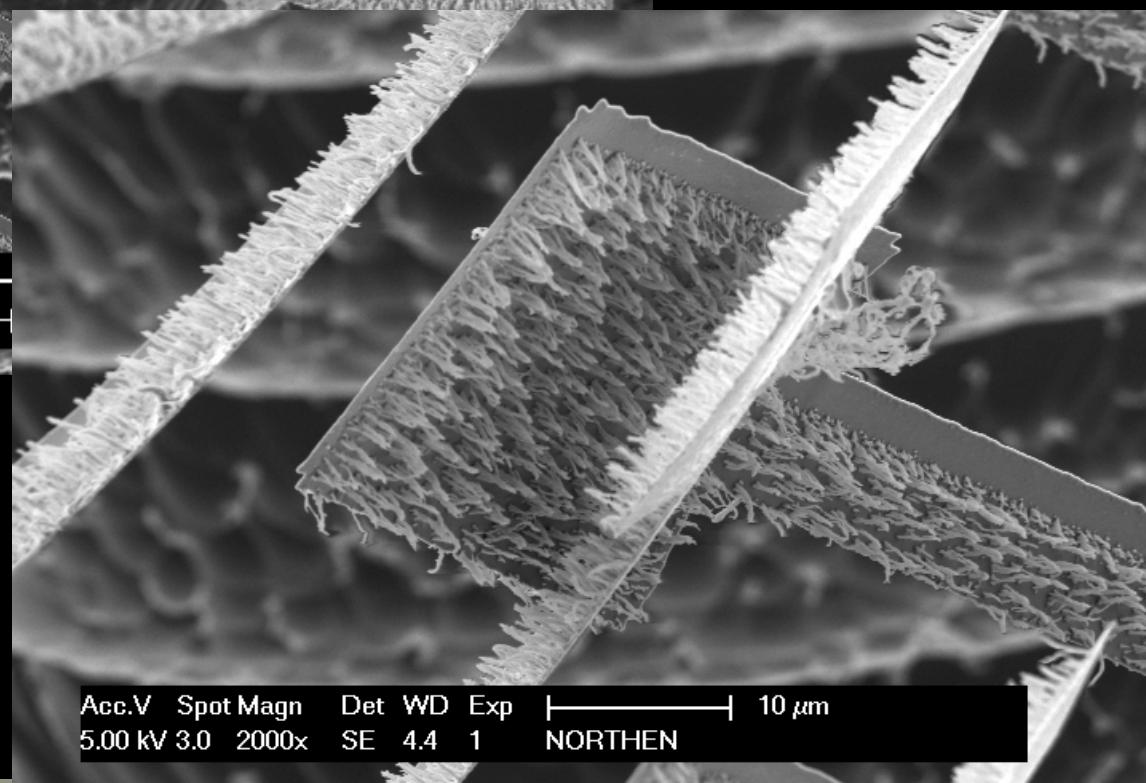
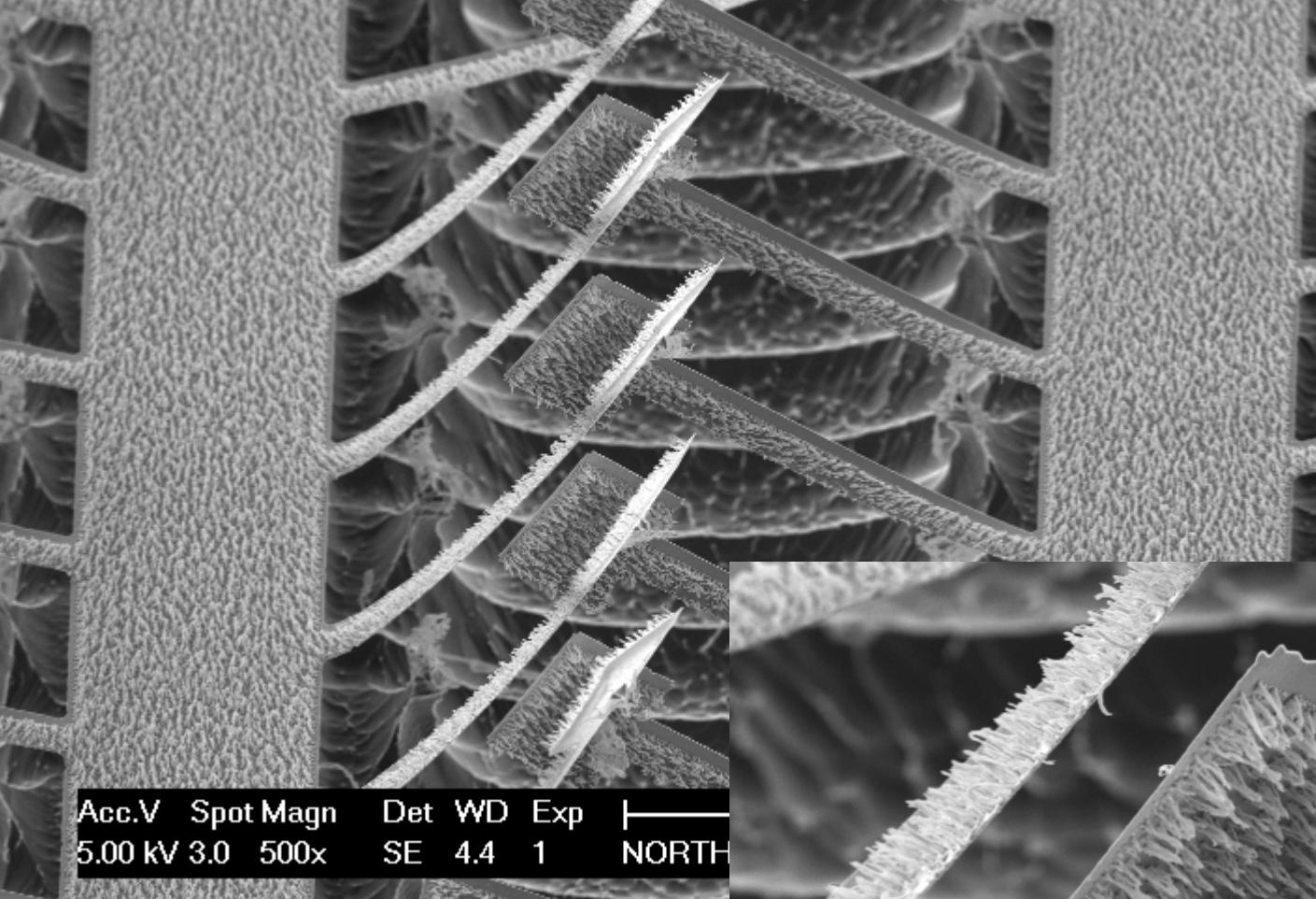
Acc.V Spot Magn Det WD Exp | 100 µm  
5.00 kV 3.0 250x SE 4.5 1 NORTHEN



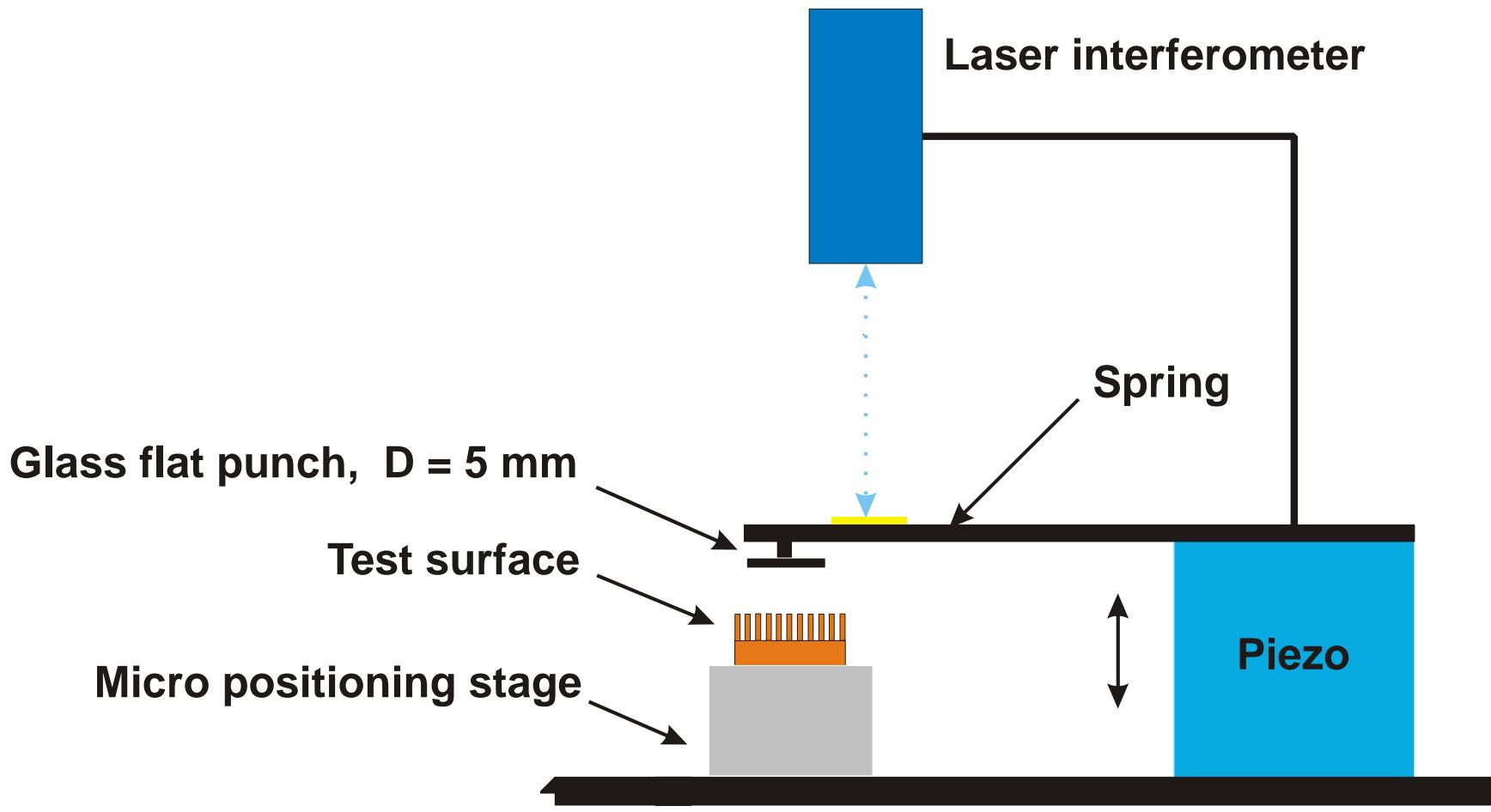
Acc.V Spot Magn Det WD Exp | 500 µm  
5.00 kV 3.0 50x SE 6.3 1 NORTHEN



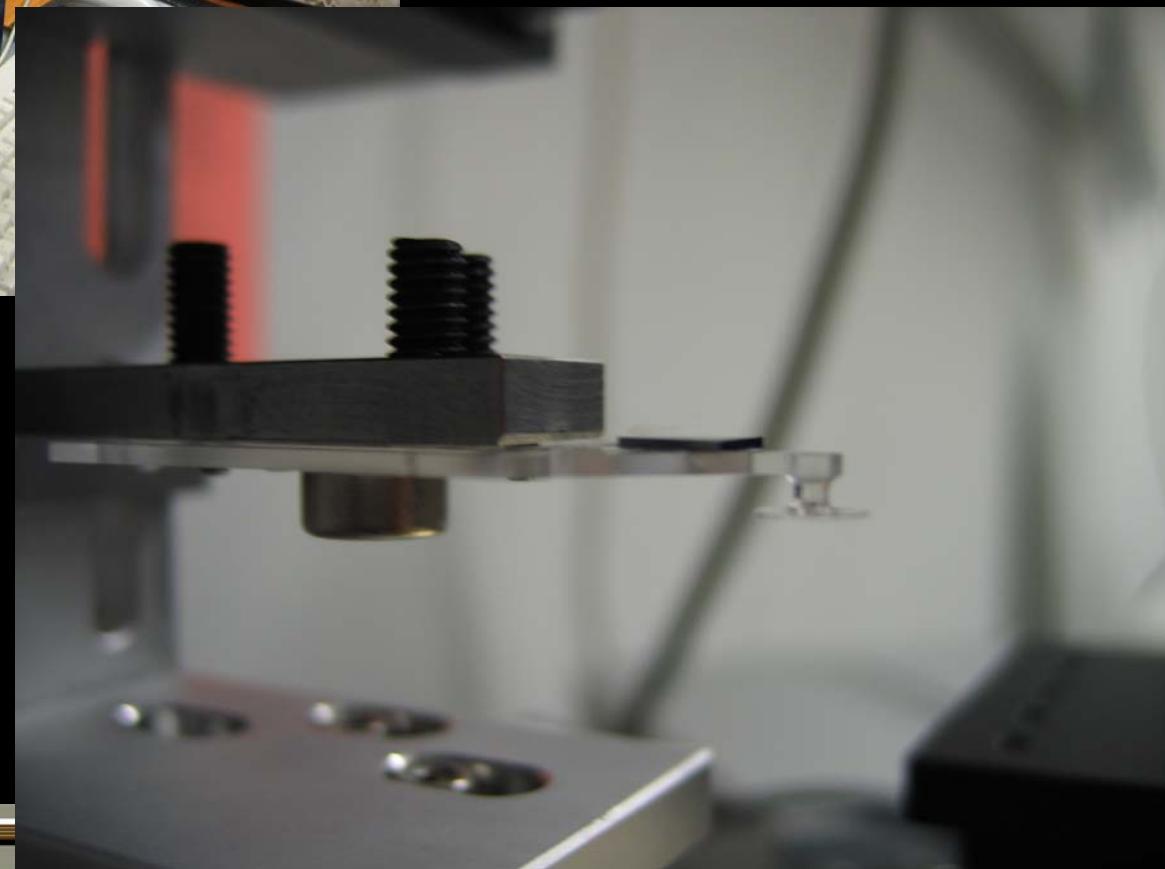


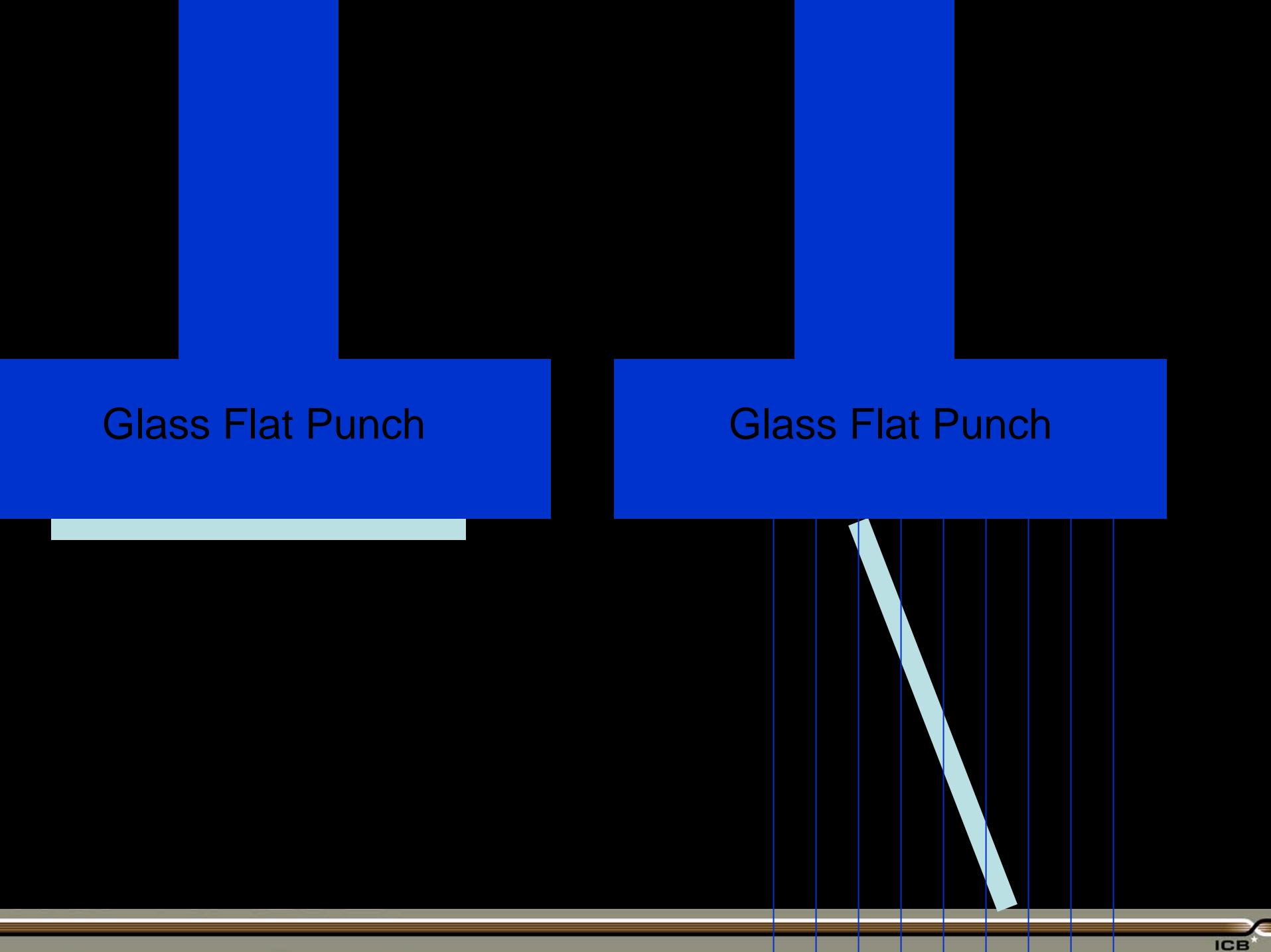


# Basalt II Adhesion Tester



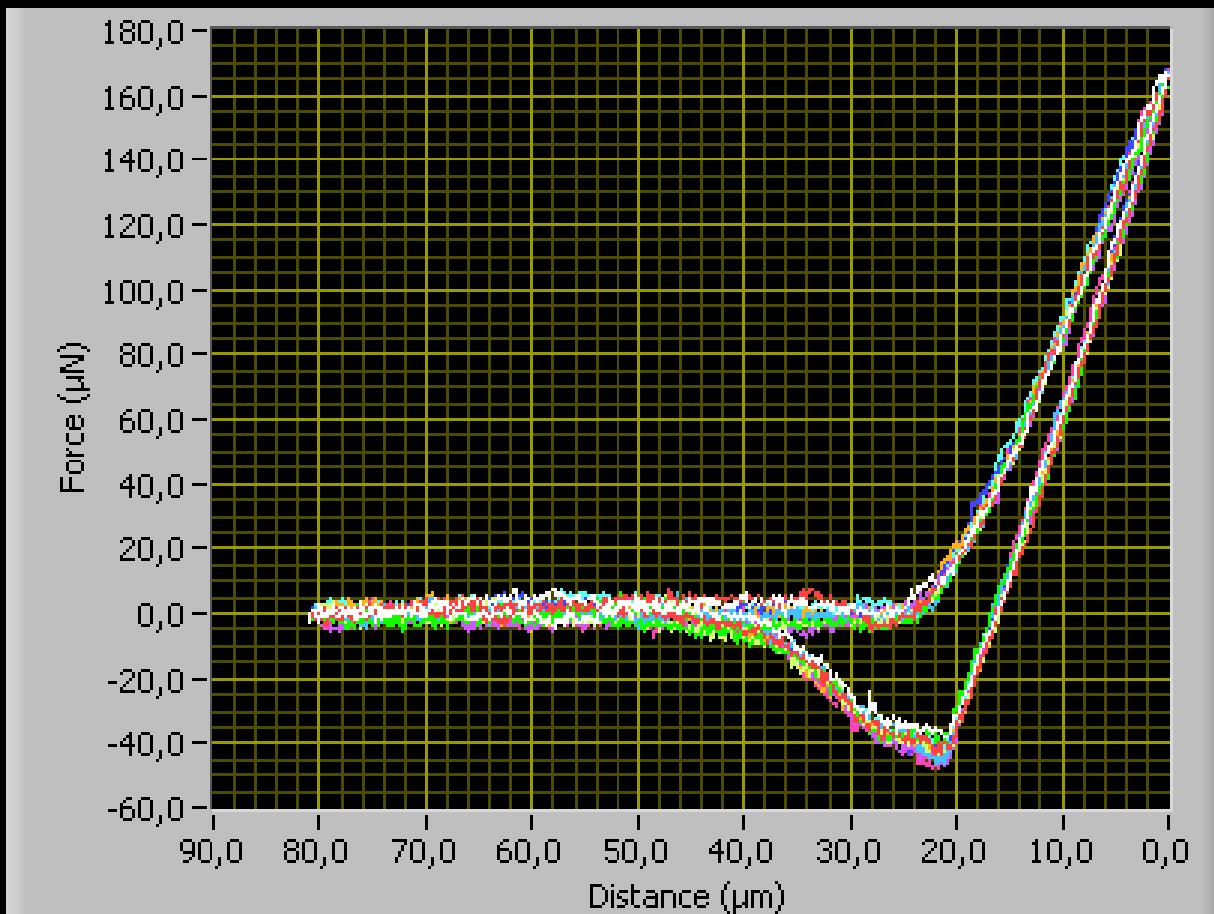
# Basalt II Adhesion Tester

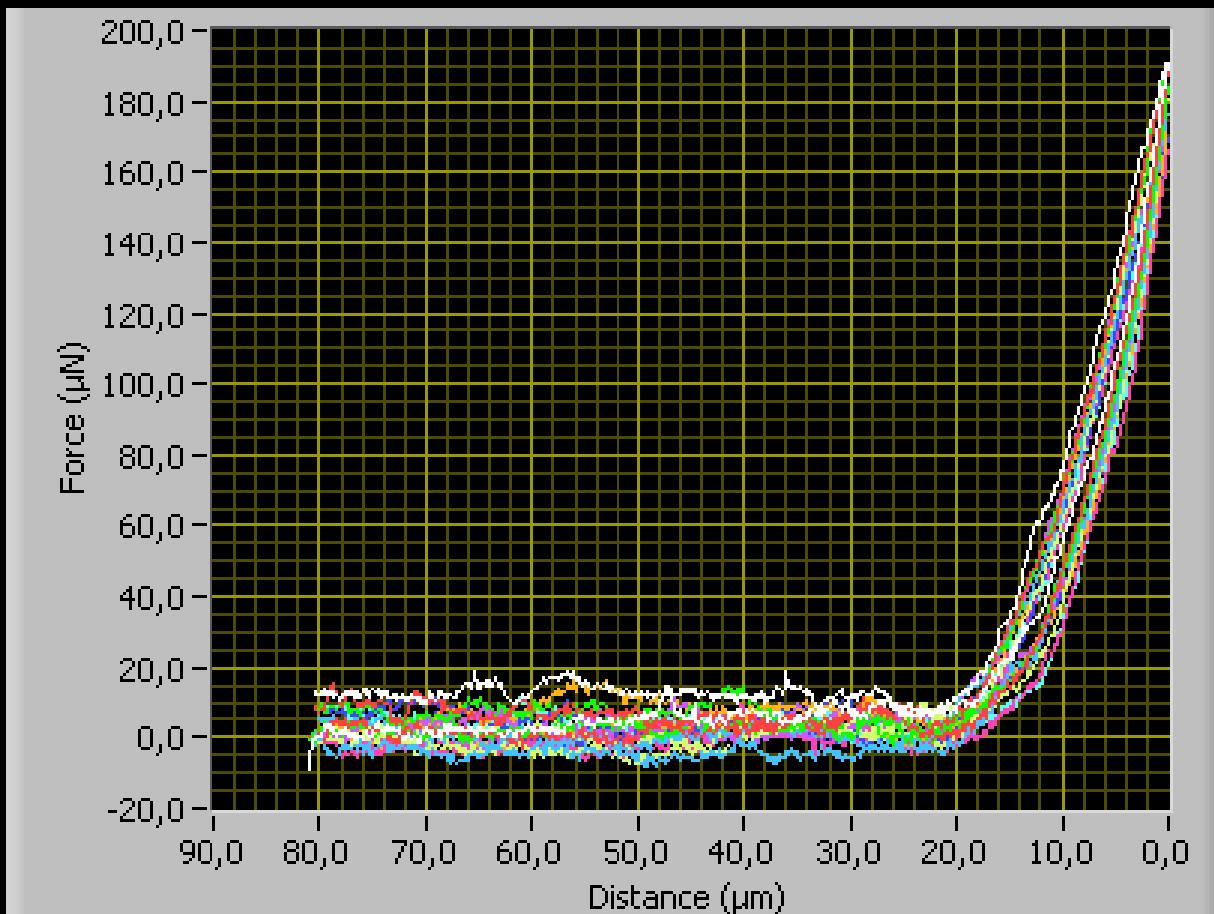


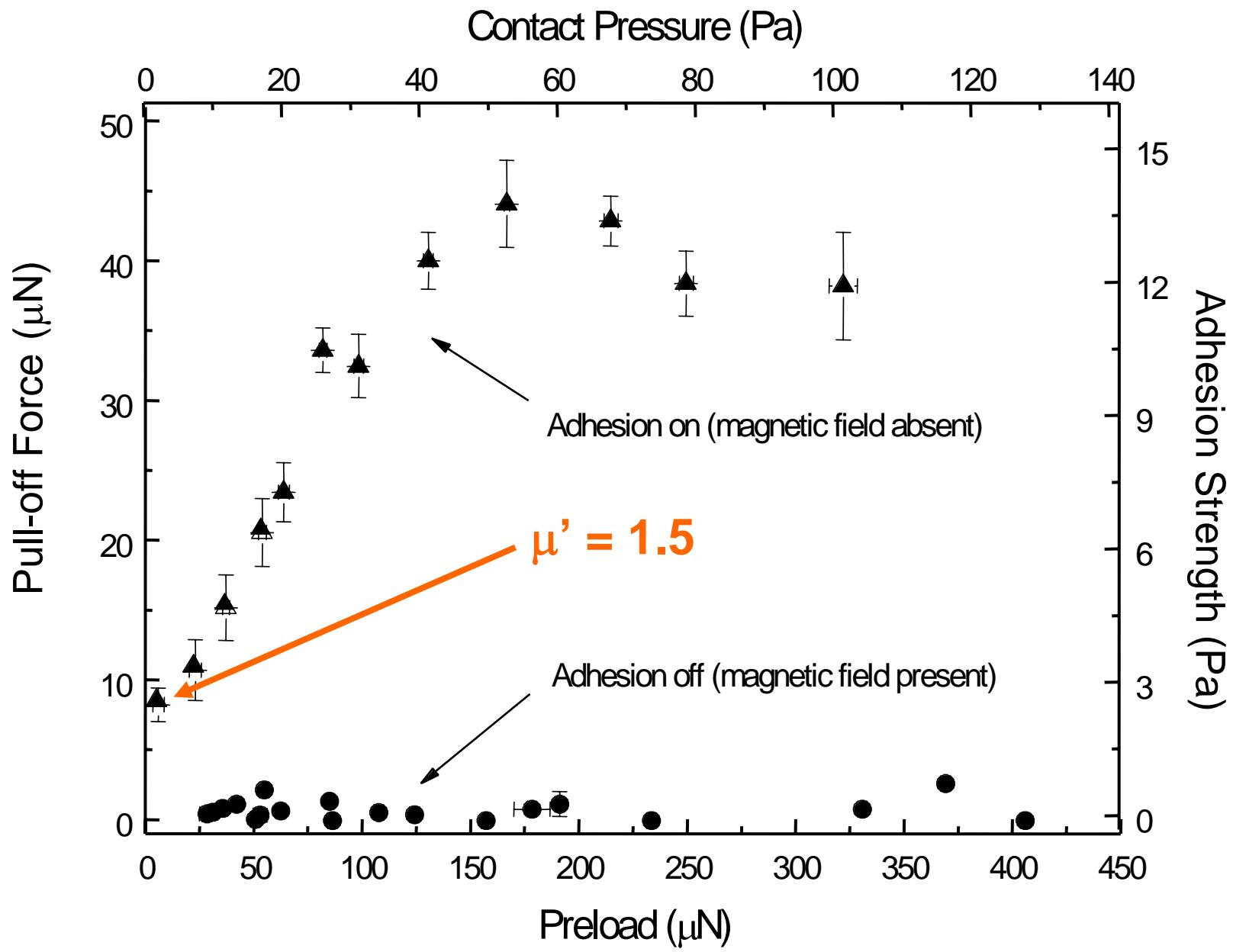


Glass Flat Punch

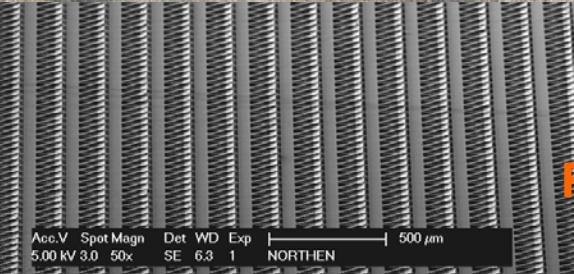
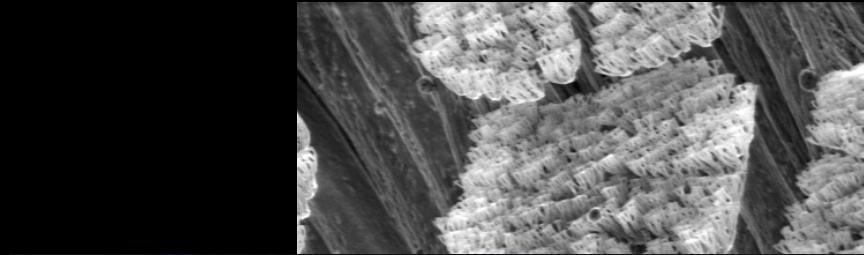
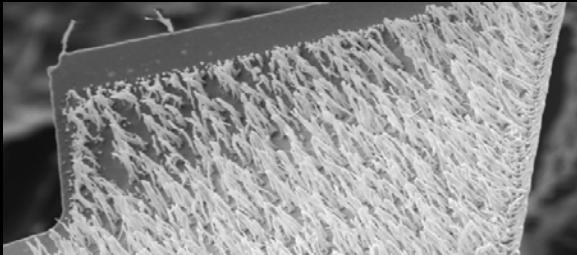
Glass Flat Punch



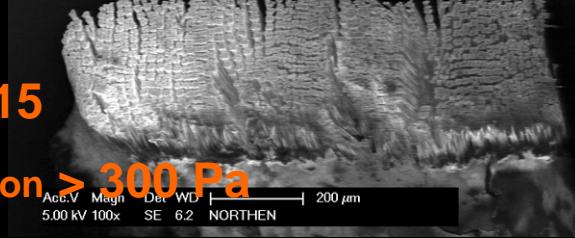




# Synthetic vs. Gecko



$\mu' = 1.5$   
Fadhesion < 15 Pa



$\mu' = 8-15$   
Fadhesion > 300 Pa



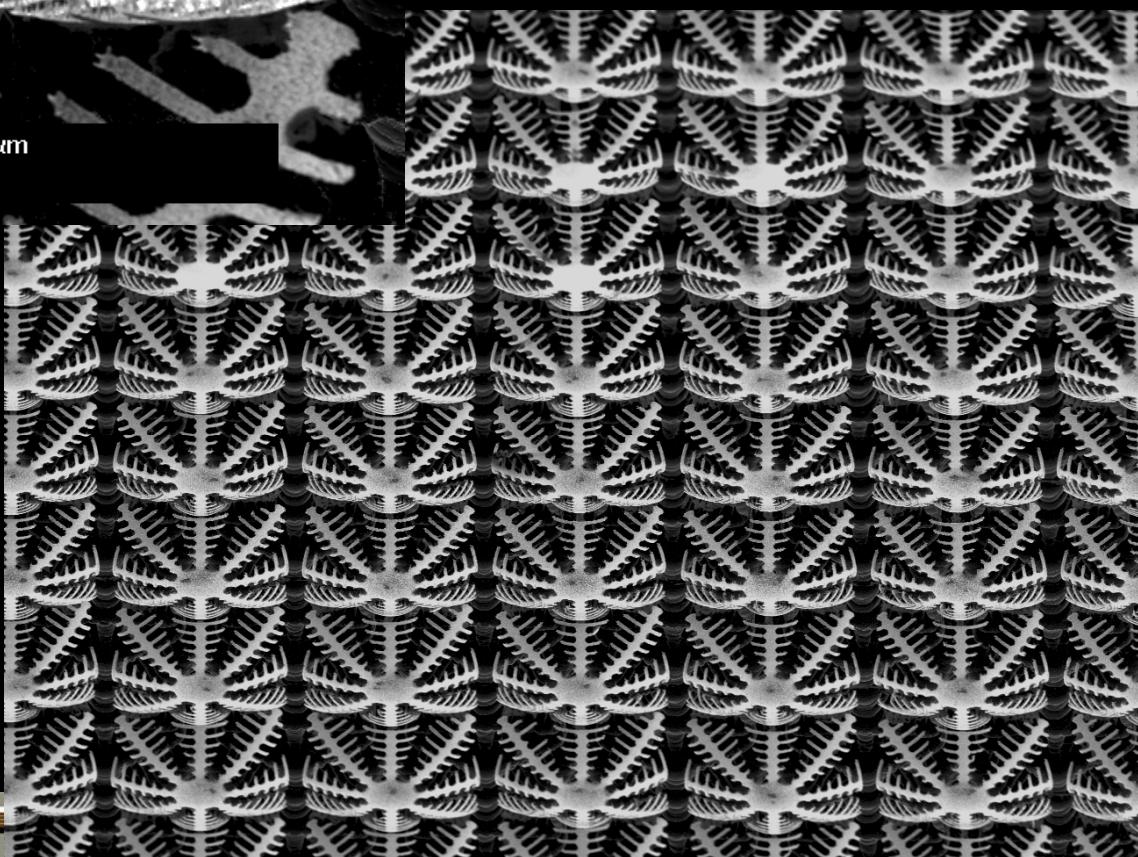
Acc.V Spot Magn Det WD Exp | 20  $\mu$ m  
5.00 kV 3.0 770x SE 5.7 1 NORTHEN

The future:

Frictional Adhesion (more  
bio-inspiration)

Increased Packing Density

Integrated Magnetic Fields



# Acknowledgements

## Funding by:

ARMY Institute for Collaborative Biotechnology

AFOSR Structural Mechanics Program



## Collaborators:

Eduard Arzt, Max Planck Institut, Stuttgart, Germany

Jacob Israelachivili, UCSB



Turner Lab: Laura Oropeza, Weibin Zhang, Michael Requa, Abhishek Srivastava, Kari Lukes, Benedikt Zeyen, Mark Zielke, Barry DeMartini

'Dude' →



## For More Information:

[www.engr.ucsb.edu/~tmems](http://www.engr.ucsb.edu/~tmems)